

# DLC layers for MPGDs

Rui De Oliveira

On behalf of the Resistive DLC Collaboration



Novosibirsk , 28-02-2020

# DLC based electrodes for future resistive MPGDs

**Title of project:** *DLC based electrodes for future resistive MPGDs*

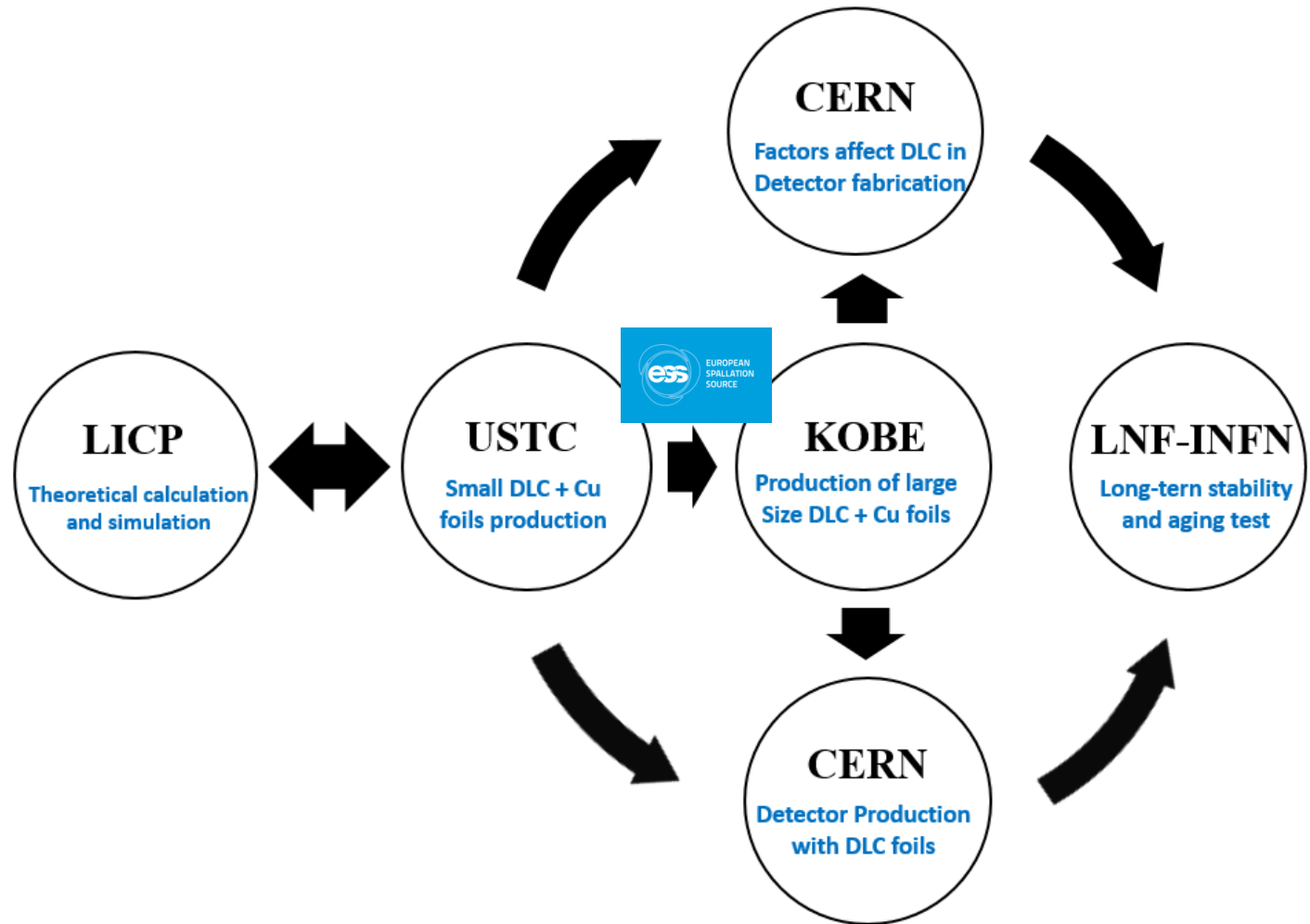
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**RD51 Institutes:**

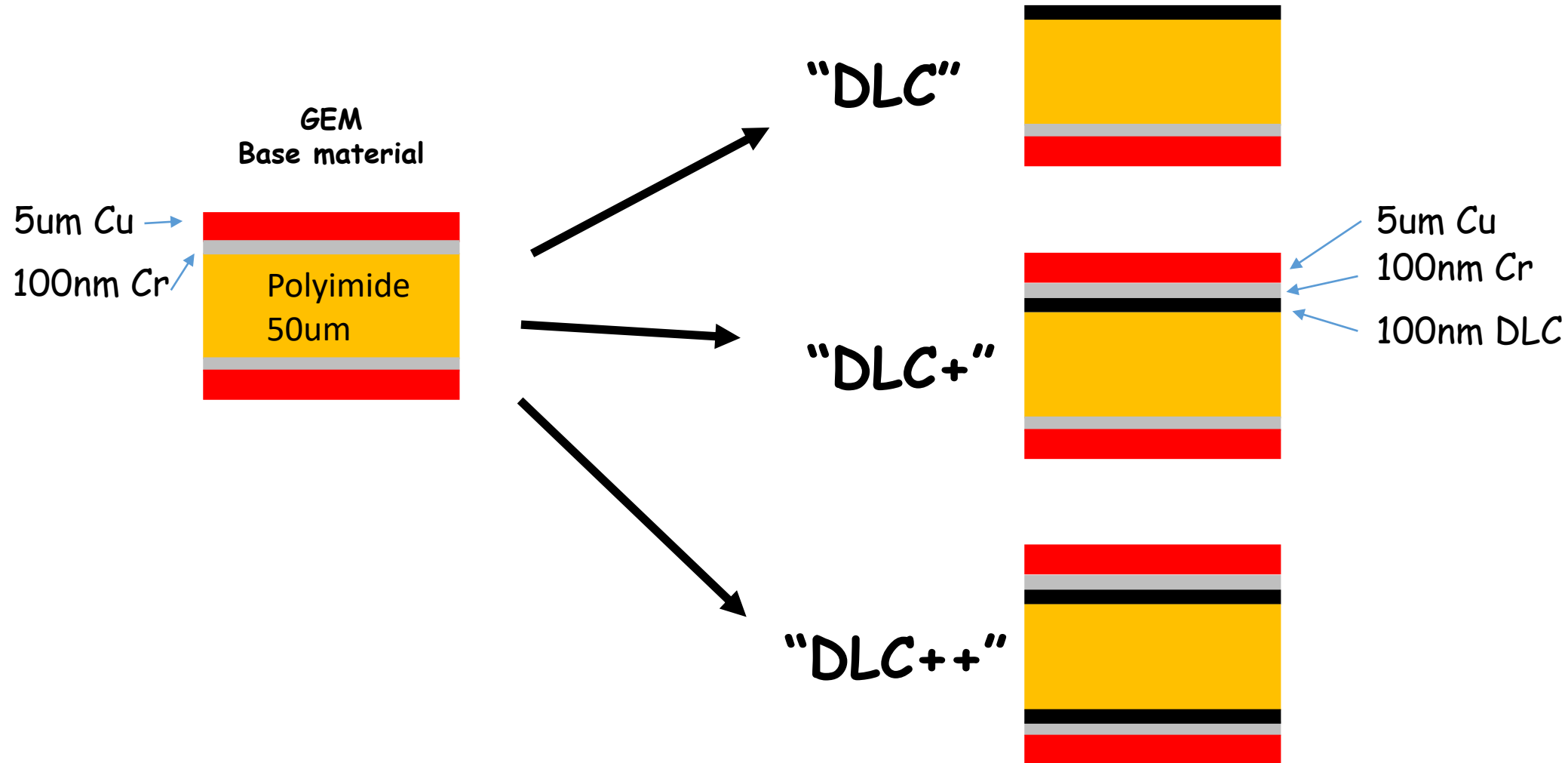
1. *State Key Laboratory of Particle Detection and Electronics, University of Science and Technology of China, contact person: Yi Zhou  
e-mail: [zhouyi@mail.ustc.edu.cn](mailto:zhouyi@mail.ustc.edu.cn)*
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e-mail: [Giovanni.Bencivenni@lnf.infn.it](mailto:Giovanni.Bencivenni@lnf.infn.it)*

**Ext. Collaborators:**

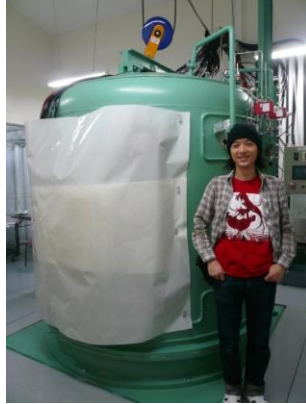
1. *State Key Laboratory of Solid Lubrication, Lanzhou Institute of Chemical Physics, Chinese Academy of Sciences, contact person: Lunlin Shang  
e-mail: [shangll@licp.cas.cn](mailto:shangll@licp.cas.cn)*



# Diamond like Carbon base material



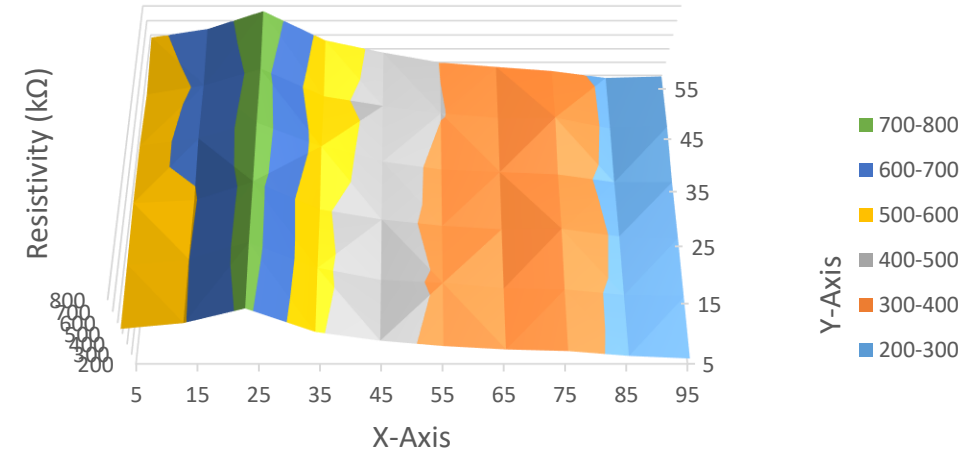
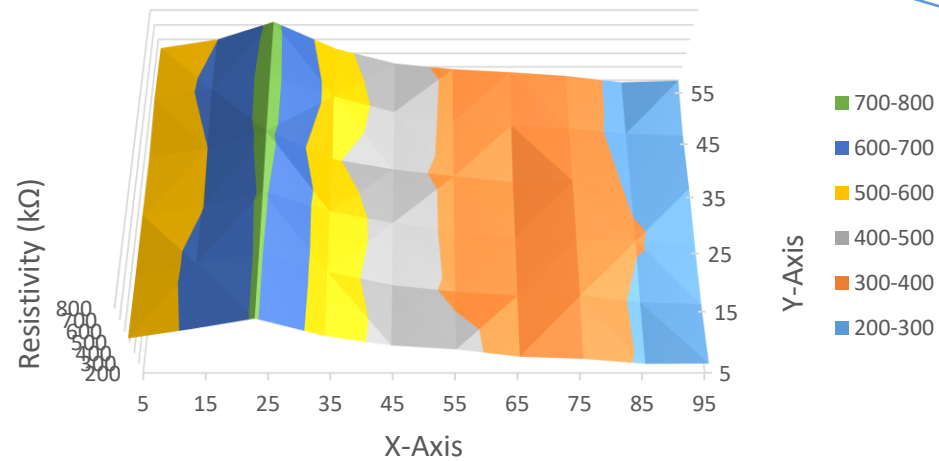
Kobe Japan  
B-sputter  
4 m x 1m real



ESS  
2.1 m x 400mm ?

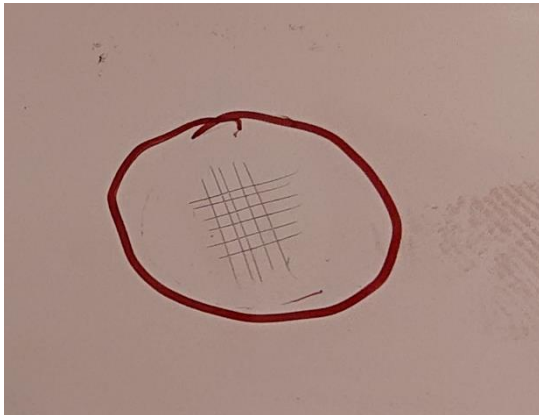
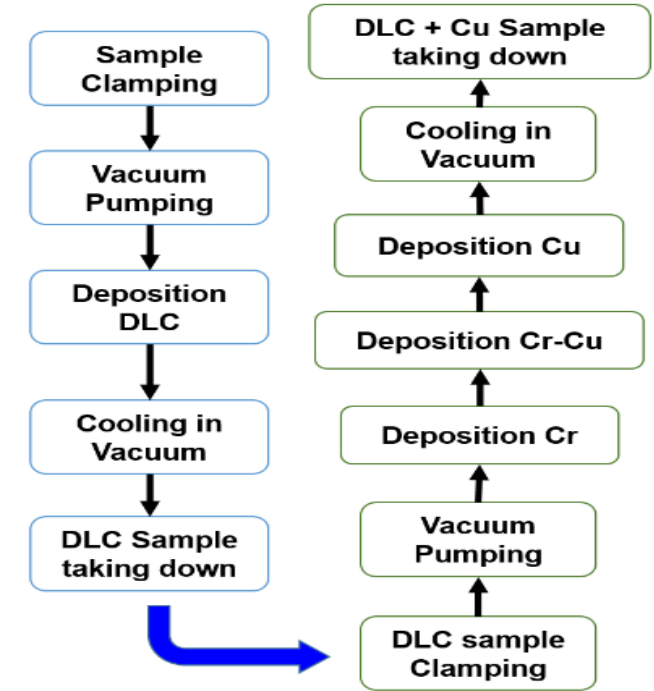
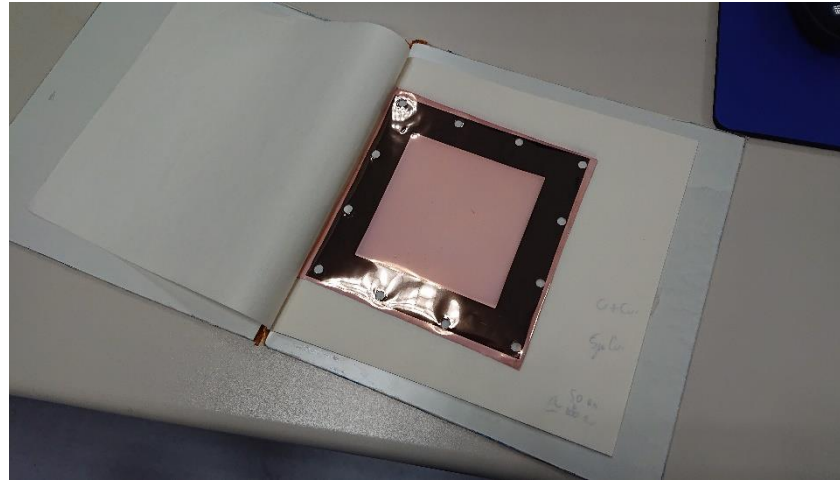
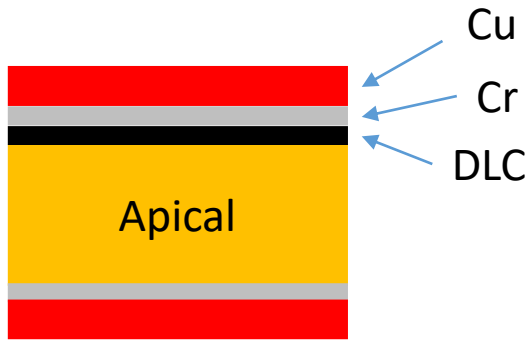


China USTC  
1.2 m x 500mm?

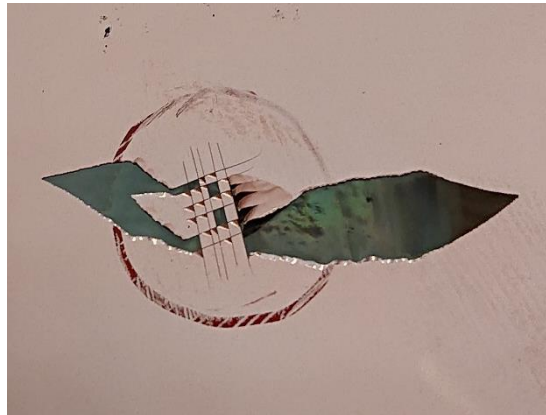


1m x 0.6m foils 500Kohms/square target

# "DLC+" adhesion test



Copper skin scalpel cut



After tape peeling

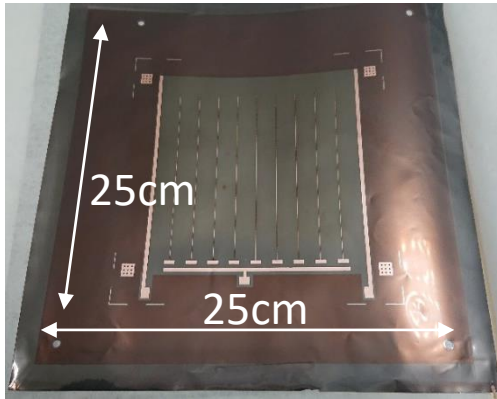
## Copper adhesion force estimation

100%	GEM Base material
50%	USTC 300 deg deposition
40%	ESS
30%	USTC

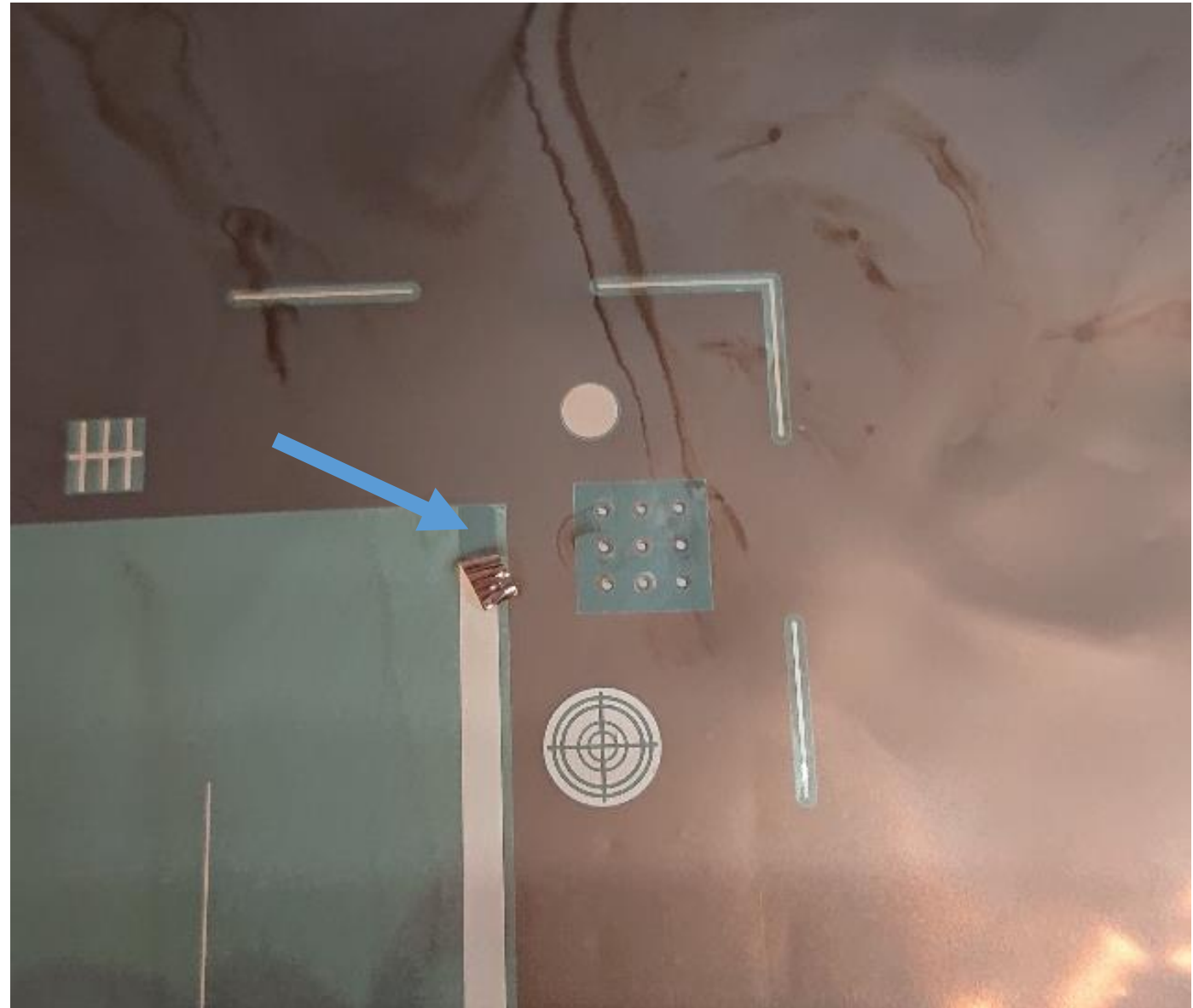
The DLC Value is always lower after copper removal ( at USTC and ESS) by a factor of 4 to 10 ?



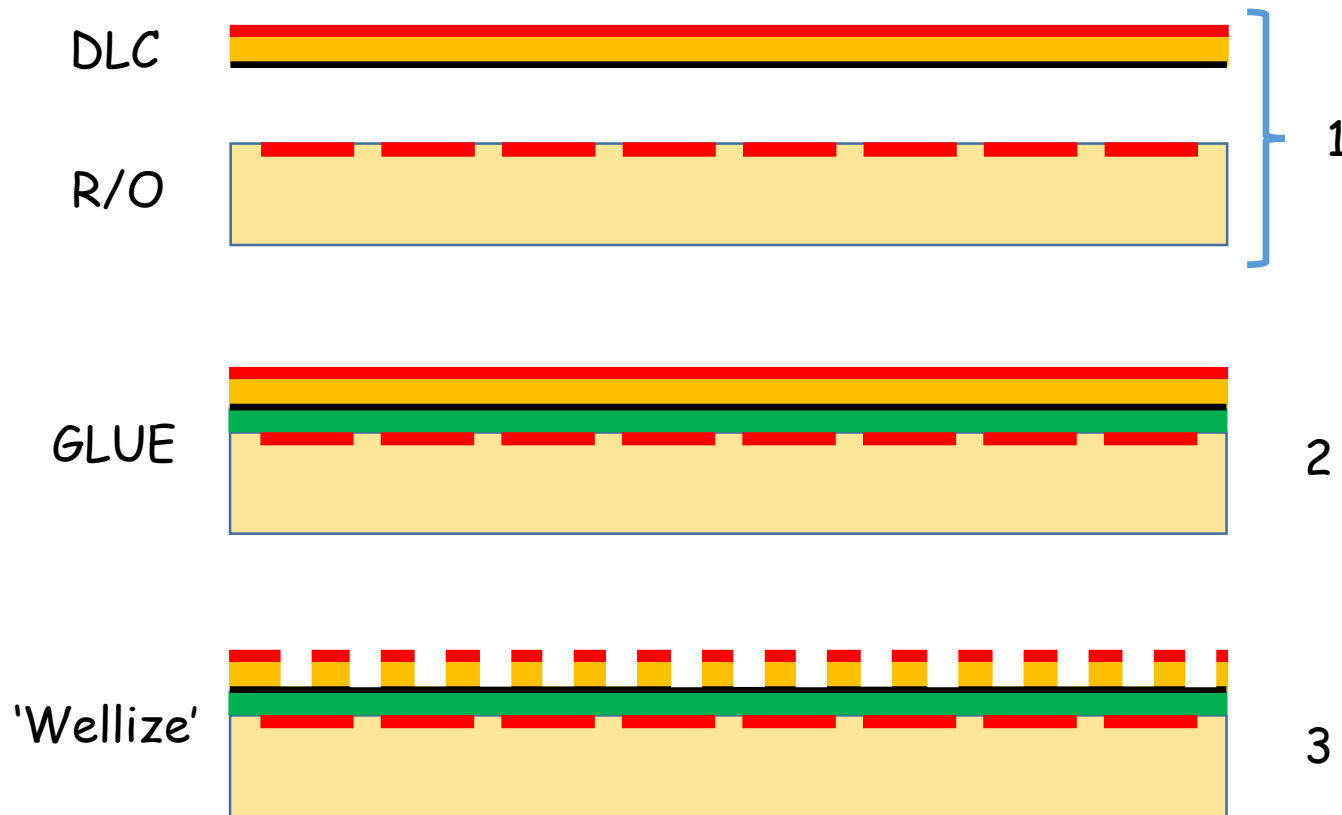
"DLC+" : present adhesion is just at the acceptable level



- 20 foils produced recently
- Really Good resistive value repeatability
- Signs of weak adhesion of Cu/Cr on DLC
- Problems on 3 foils over 20



# STD $\mu$ Rwell production steps



- Really simple construction
- Flexible
- Low cost
- Low mass  $< 0.15\%X_0$

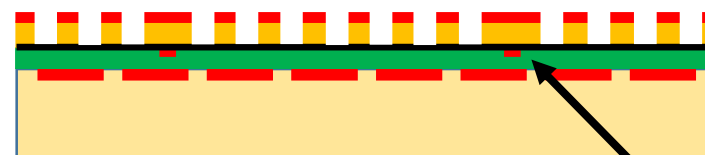
- rate limitation



Large  $\mu$ Rwell detector  
Like CMS GE21 module M4  
120cm x 55cm

# Different high rate $\mu$ Rwell structures

SG



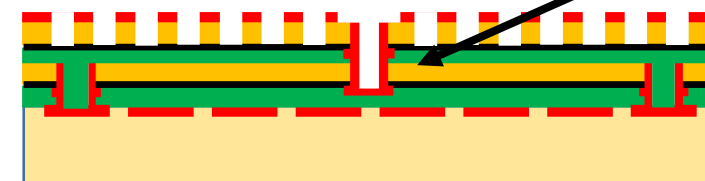
- 1 "DLC+" with Silver or Cu evacuation Grid

DF



- 1 "DLC" with Drill and fill method

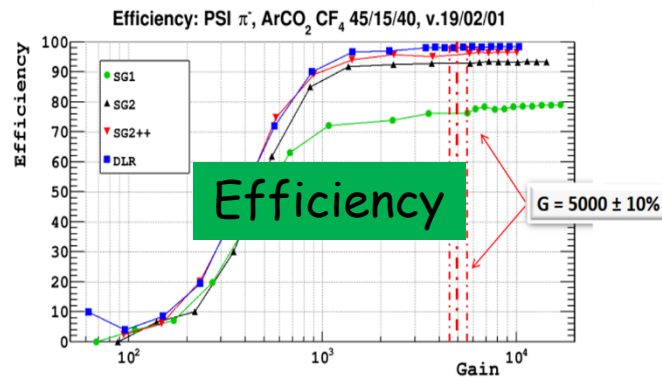
SBU



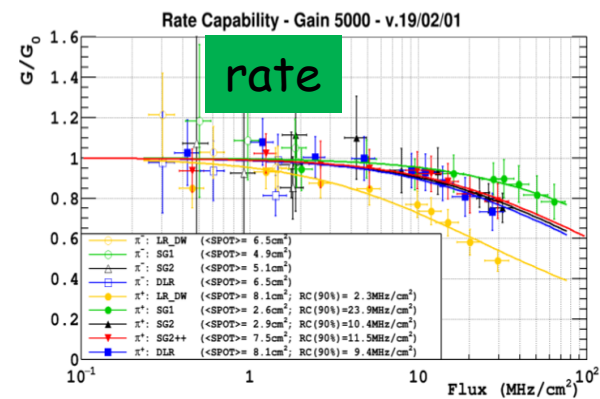
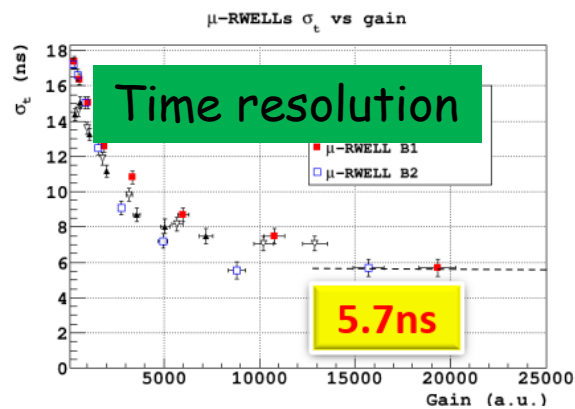
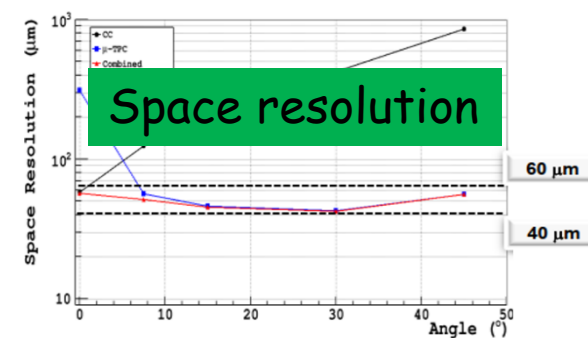
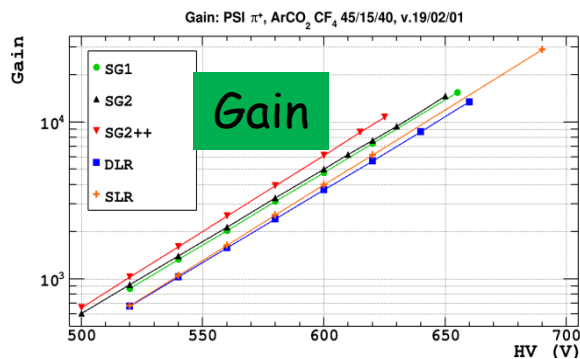
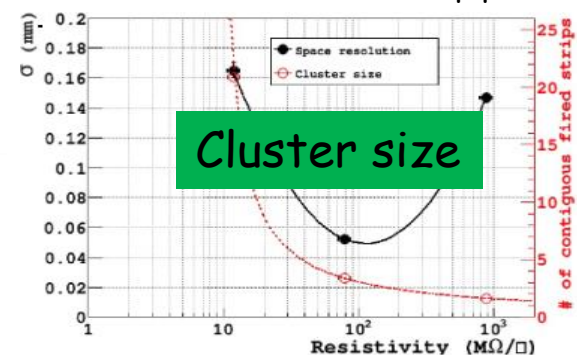
- 2 "DLC+" Sequential Build Up

Local Charge Evacuation





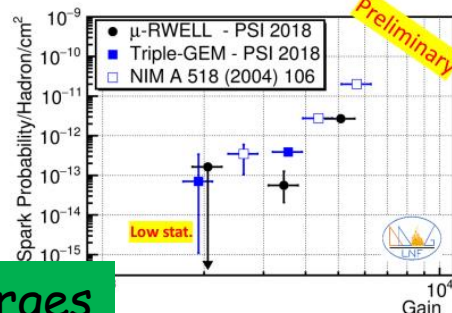
0.4mm strip pitch



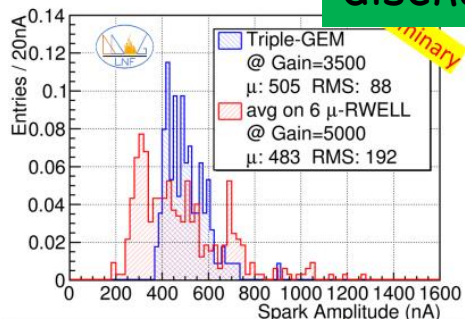
## Discharge studies

The  $\mu$ -RWELL discharge probability measured at the PSI, and compared with the measurement done with GEM at the same time and in the 2004 (same gas mixture - Ar:CO<sub>2</sub>:CF<sub>4</sub> 45:15:40).

The measurement has been done in **current mode**, with an intense 270 MeV/c  $\pi^+$  beam, with a proton contamination of the 3.5%.



discharges



"discharge" has been defined as the current spike exceeding the steady current level correlated to the particle flux (~90 MHz on a ~5 cm<sup>2</sup> beam spot size).

The discharge probability for  $\mu$ -RWELL comes out to be slightly lower than the one measured for GEM.

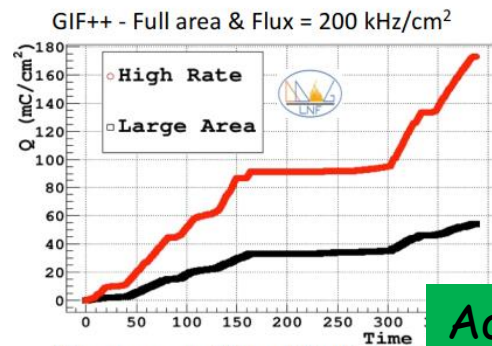
Moreover its discharge amplitude seems to be lower than the one measured for GEM.

M. Poli-Lener, MPDG 2019 - La Rochelle, 10/05/2019

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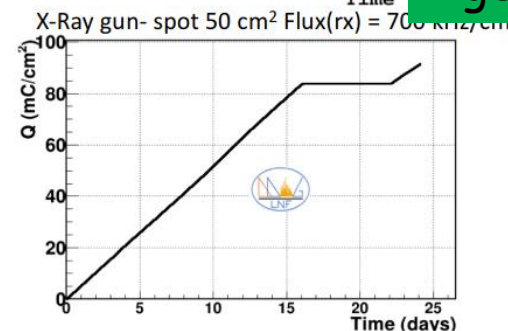
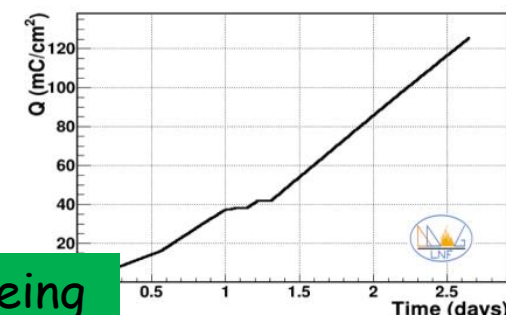
+Material long term stability

## Ageing studies (on going)



Ageing

TB PSI - beam spot 9 cm<sup>2</sup> - Flux= 10 MHz/cm<sup>2</sup>



**GOAL:**  
Integrate a charge up to 6 C/cm<sup>2</sup>

Slice test of u-RWELLs  
during RUN3 in the LHCb  
Muon APPARATUS under  
discussion

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# Protections to survive overvoltage

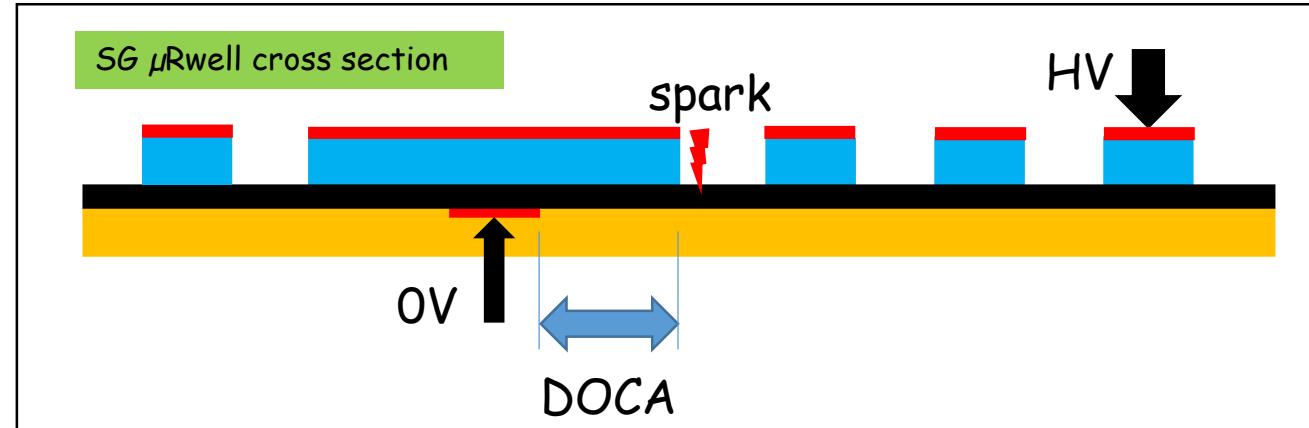
# Overvoltage means sparks

→ Possible voltage breakdown of materials and large local energy release  
 → DOCA protection (Distance Of Closest Approach)

## Breakdown voltage

PI	420 V/um
Perfect DLC	650 V/um
real DLC (average)	10 V/um
Copper	NA

Of course, dielectric strength are greatly impacted by impurities, dopants, structure, interconnected porosity, flaws and micro-cracks from thermal expansion mismatches



## First problem: DLC layer breakdown due to the voltage set by the spark.

-if DLC is damage by Voltage Breakdown → no spark control

- Good DOCA cancel this problem

## Second problem : electron/ion bombardment during spark

- bombardment → temperature rise due to joule effect → material evaporation → material condensation → current instabilities

- Bombardment effects can be mitigated

-avoid repetitive sparks → remove contaminants (dust, ions from chemicals).

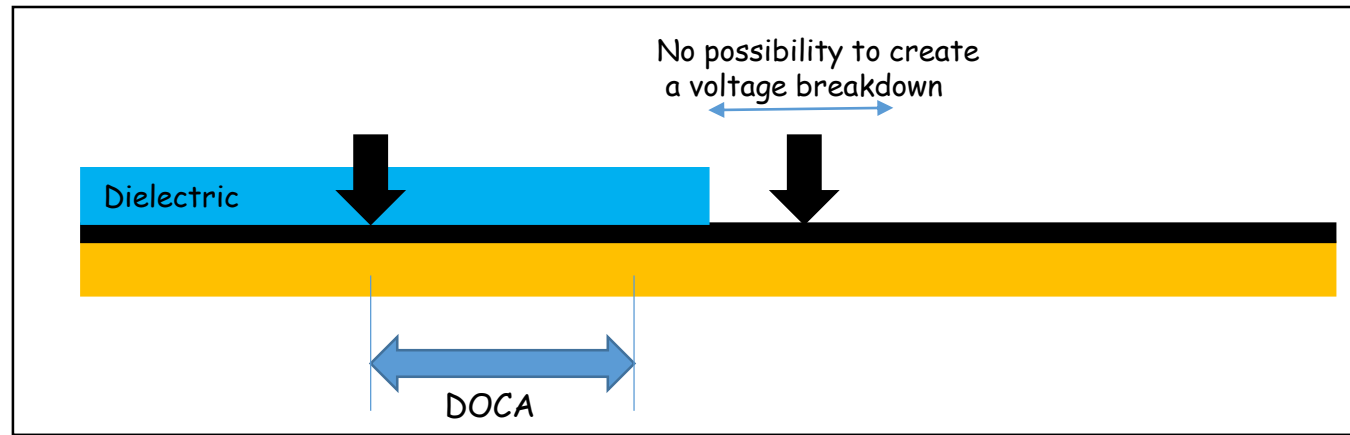
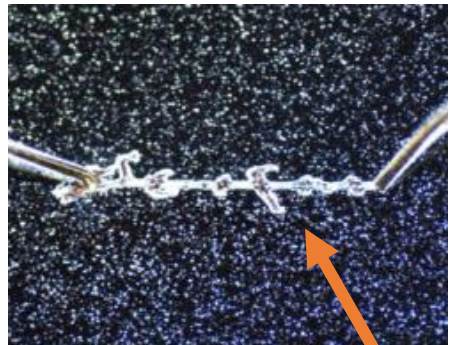
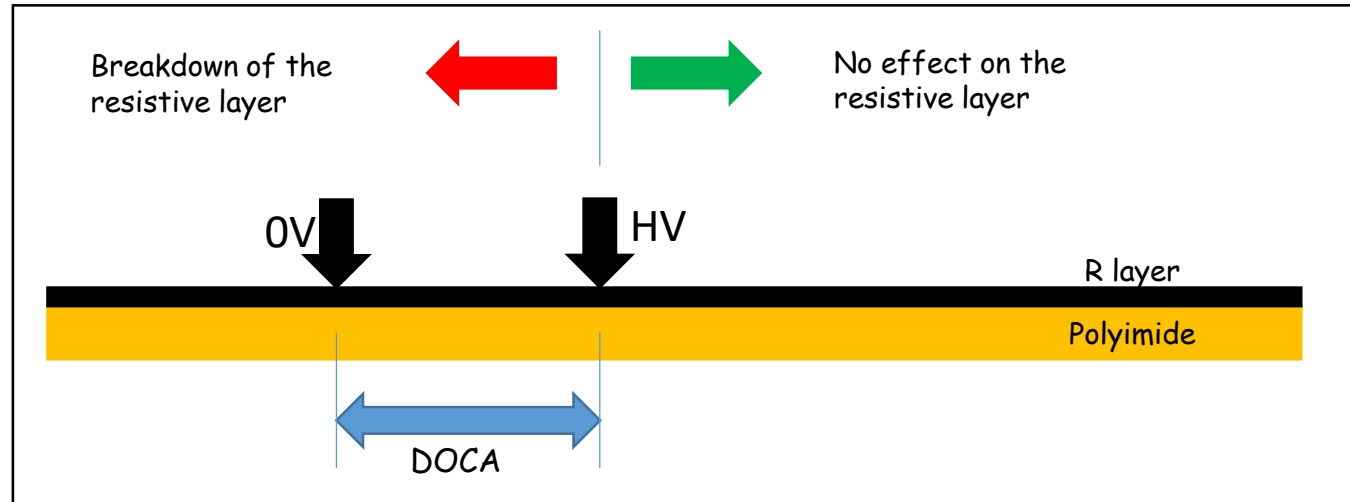
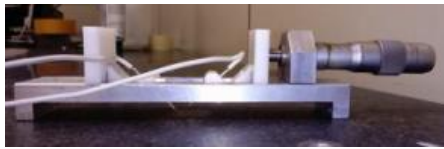
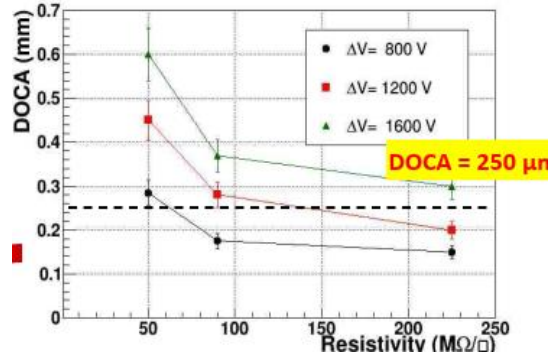
- choose high melting temperature materials to lower the evaporation

-choose good thermal conductivity & thicker layers materials to cool the reaction

-DLC value can reduce spark energy

Material	Thermal conductivity W/mK	Melting Celcius
<a href="#">Glass epoxy</a>	0.2	200
<a href="#">PI</a>	0.18	400
<a href="#">Copper</a>	384	1085
<a href="#">Natural diamond</a>	1350	700

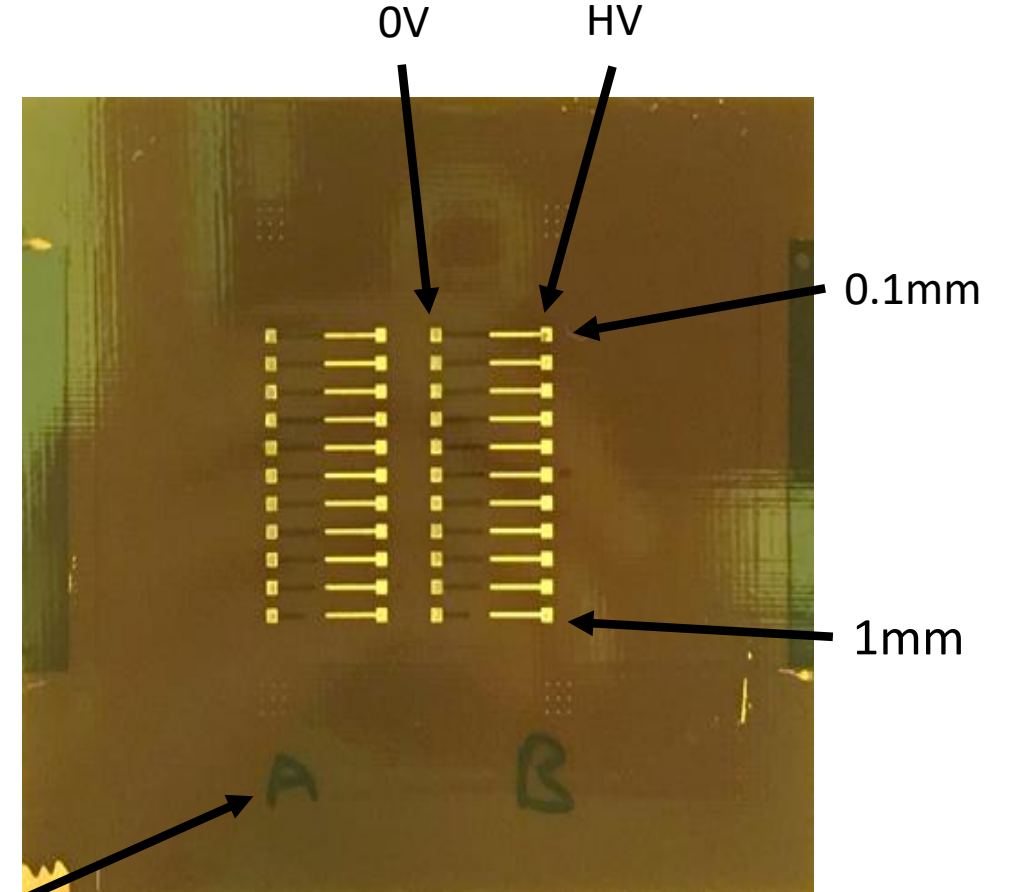
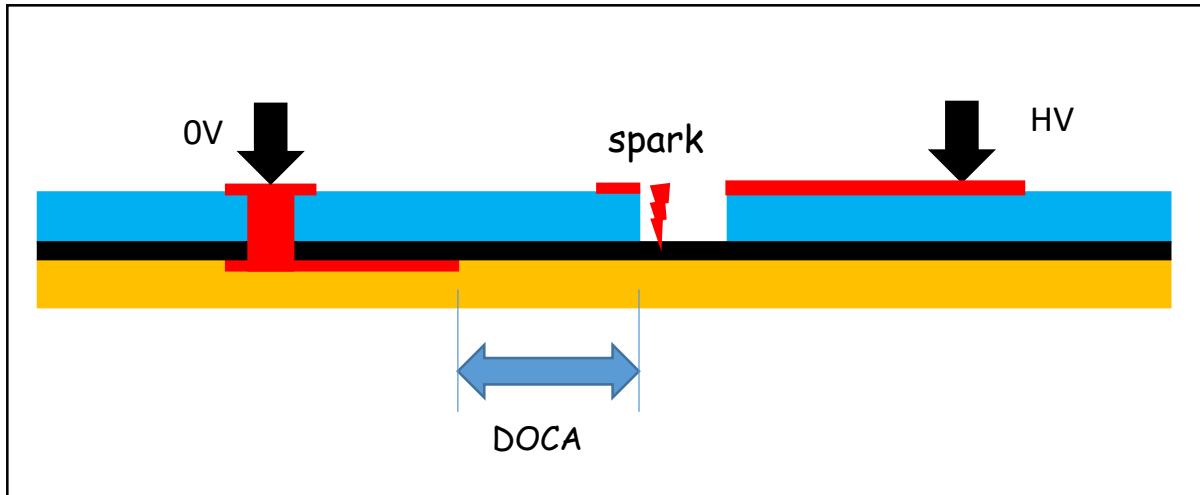
# DOCA to prevent DLC BV



A breakdown of the resistive layer means creating a low Ohmic channel in the layer



# test with real sparks

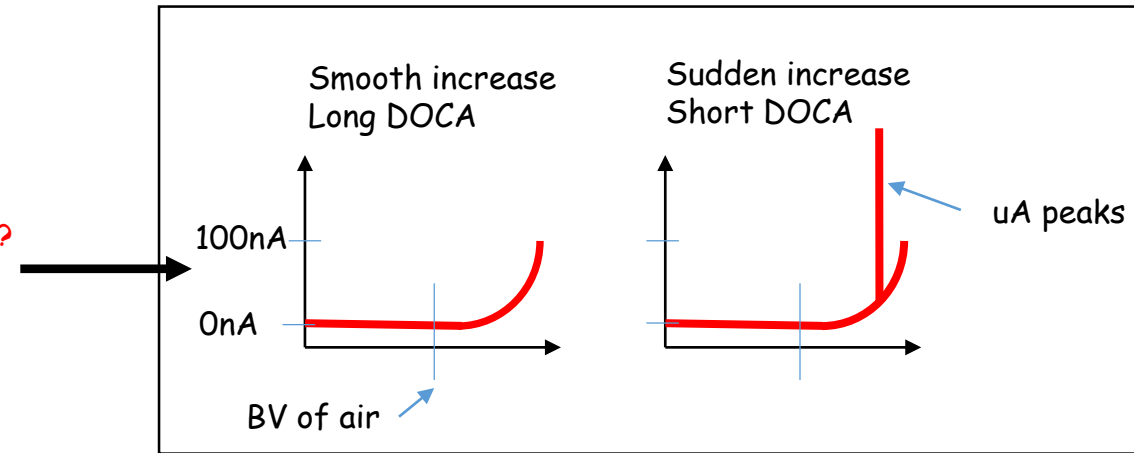


- Columns of 11 patterns → DOCA ranging from 0.1 up to 1 mm
- Single hole test
- DLC 60M-70M/Sqr
- 4 columns of 11 patterns have been tested (A,B,C,D)



# Observations

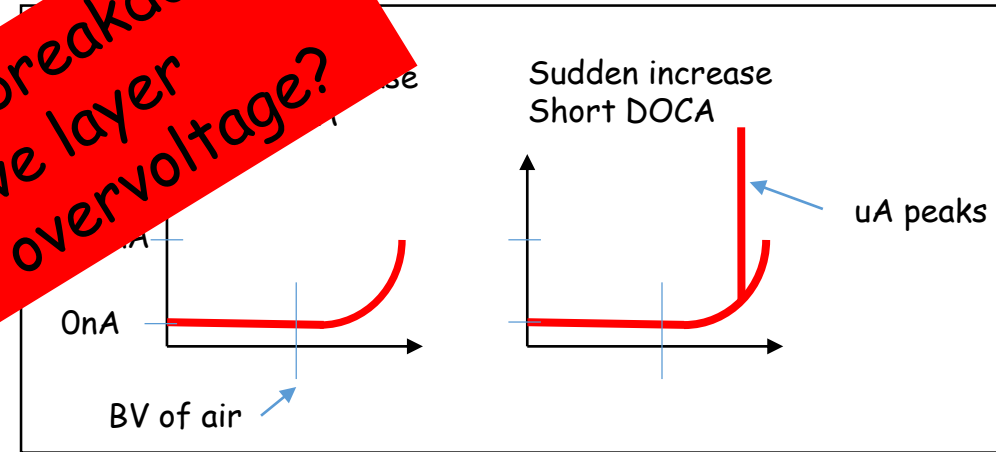
- Leakage current start at 800V in air!
  - We were expecting 650V air BV for a 50um gap (like GEMs)
- The current shape during overvoltage depends on DOCA distance
  - Smooth current increase with long DOCA → small material deposition after evaporation ?
  - Sudden increase to uA with small DOCA → larger deposition ?
- After 30 sec with 30nA in one hole we start to see voltage drop
  - After several session of 30s , it stabilize at 550V / 650V (0 current voltage)
  - No visible damages on any structures.
  - There is obviously electric signs of material deposition
  - Unfortunately it was impossible to count sparks
- Next step will be to look at the "sparks" current shape when operating above Air BV
  - We would like to study the single hole spark current shape and rate with a fast oscilloscope .
  - This is possible with DLC since we have time before damaging the device
- Preliminary results : with 60Mohms/Sqr DLC , the DOCA can be as low as 0.1mm without visible damages



# Observations

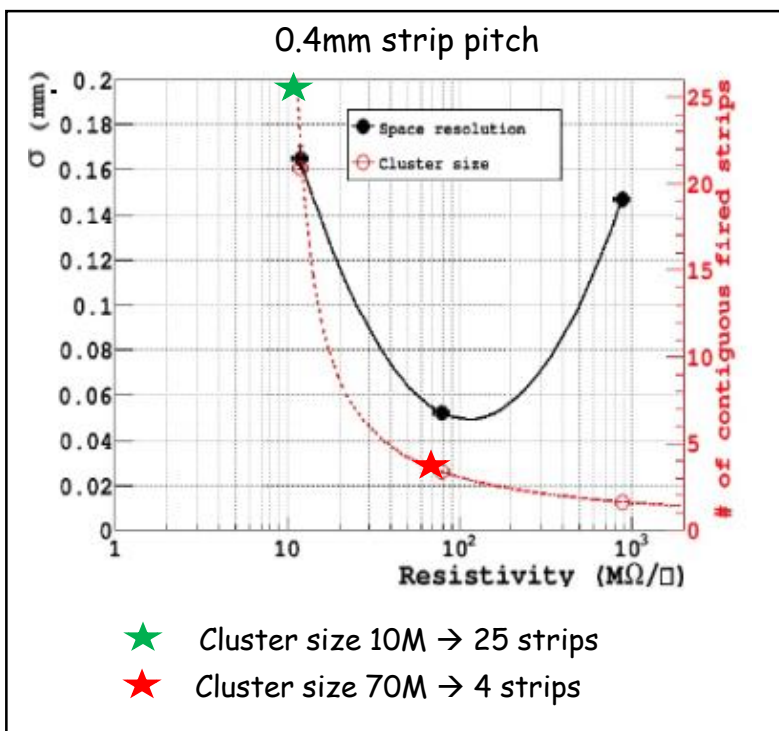
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  - There is obviously electric signs of material deposition
  - Unfortunately it was impossible to count
- Next step will be to look at the current shape when operating above Air BV
  - We would like to study the current shape and rate with a fast oscilloscope .
  - This is possible with DLC since it is not damaging the device
- Preliminary results : with 6000ns/Sqr DLC , the DOCA can be as low as 0.1mm without visible damages

We were looking for resistive layer breakdown  
→ No breakdown of the resistive layer  
instead 2 different behaviours at overvoltage?

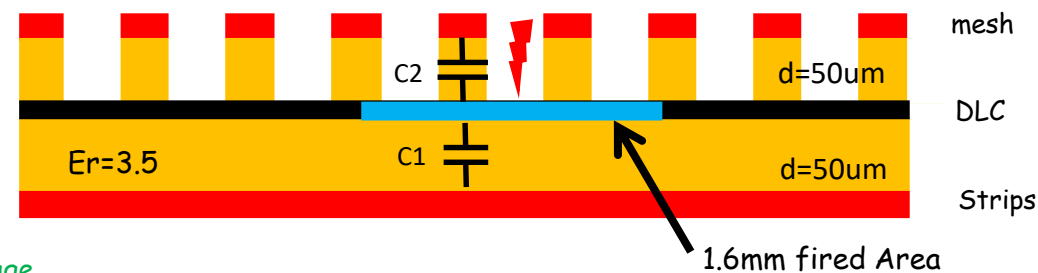


# What is the energy released level during spark ?

1 X

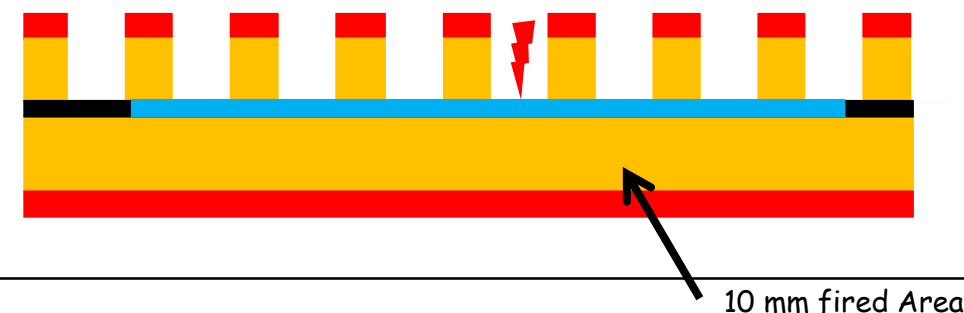


★ 70M DLC  $\rightarrow$  4 strips fired  
fired area : 1.6mm diameter  
"fired area" capacitor  $C=C_1+C_2$   
 $C_1 = \epsilon_0 \times \epsilon_r \times A/d \rightarrow 2\text{pF}$   
 $C=C_1+C_2 \rightarrow 4\text{pF}$   
 $E=1/2 CV^2$   
 $E=0.5\text{ uJ} \rightarrow$  reference energy  
Smooth current increase in overvoltage



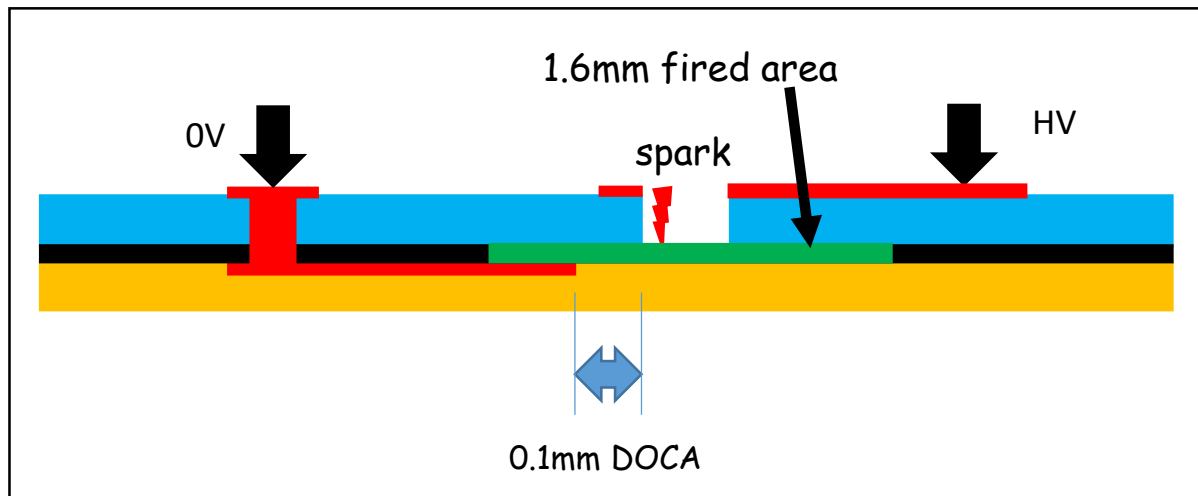
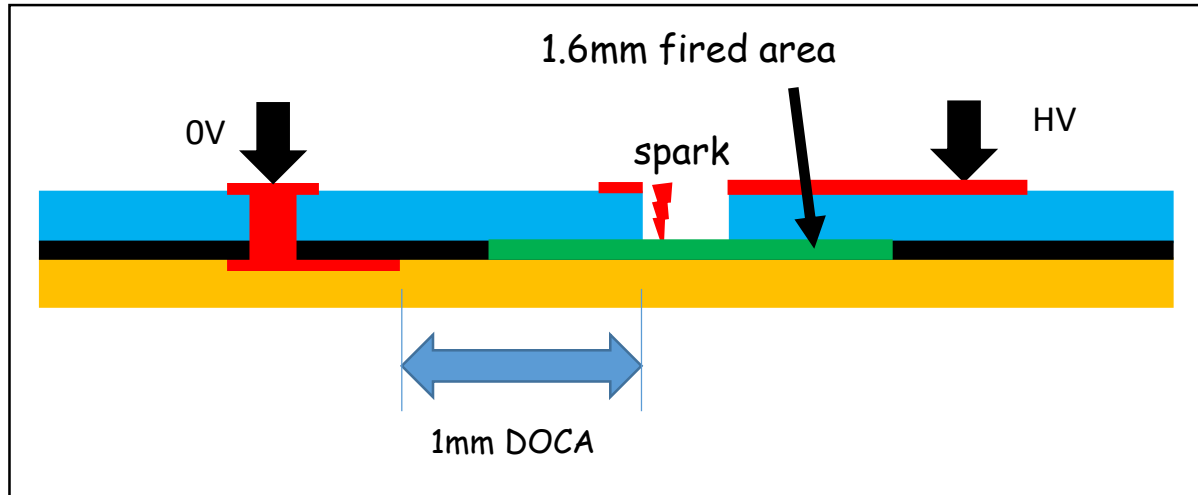
25 X

★ 10M DLC  $\rightarrow$  25 strips fired  
fired area : 10mm diameter  
 $C=C_1+C_2 \rightarrow 100\text{pF}$   
 $E=12.5\text{ uJ} \rightarrow 25\times$  more energy  
High current spikes in overvoltage

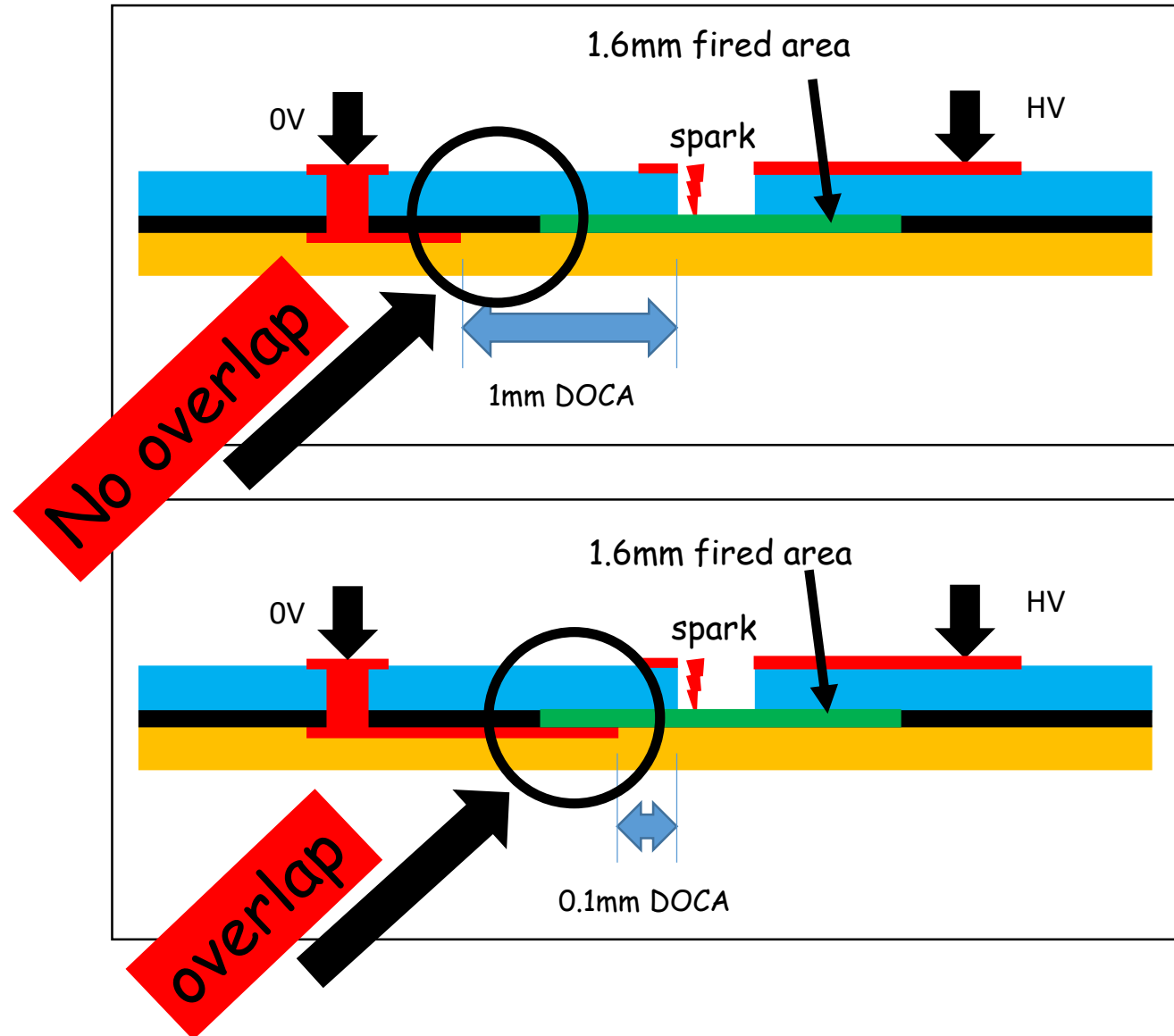


1000 X for a 10cm x 10cm GEM

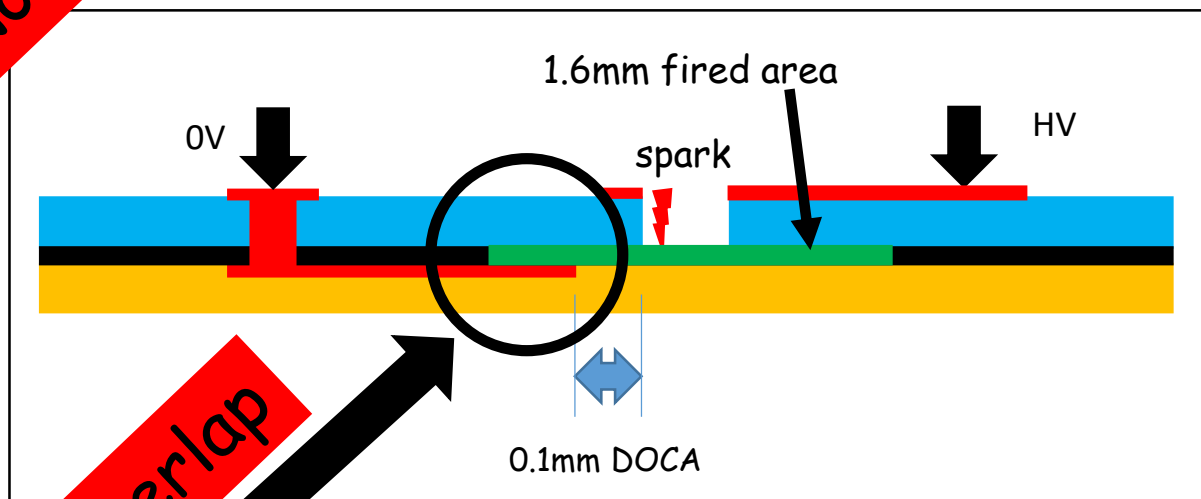
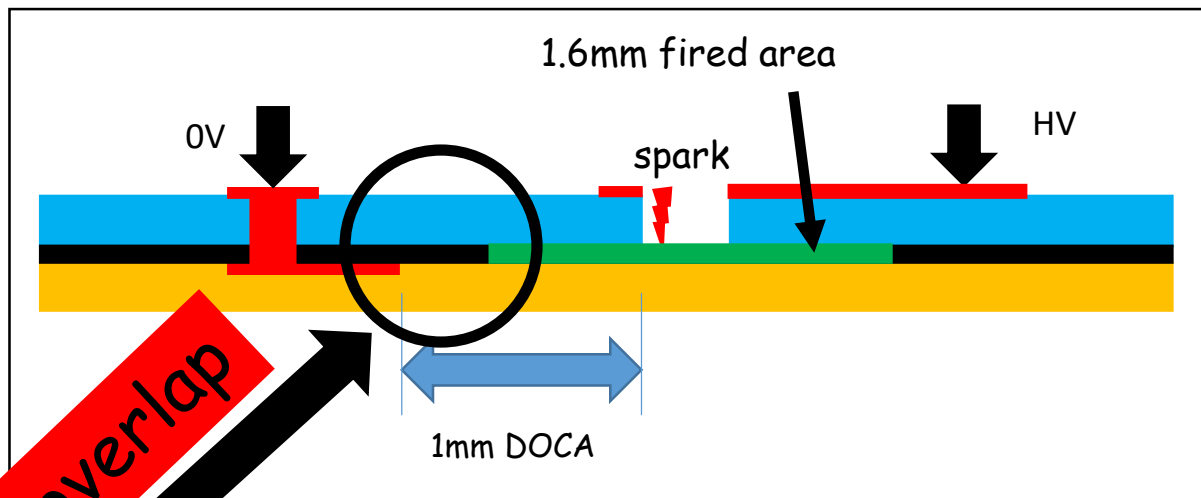
# Possible explanation of the DOCA Test results ?



## Possible explanation of the DOCA Test results ?

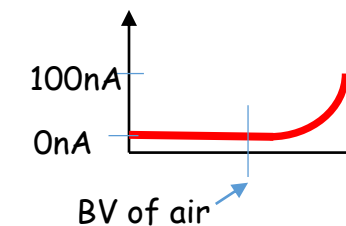


# Possible explanation of the DOCA Test results ?



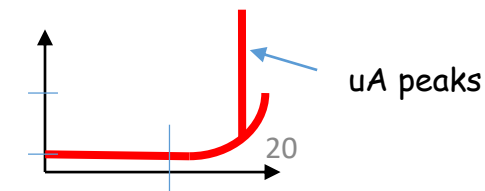
The spark energy comes only from the fired area capacitor

We keep control



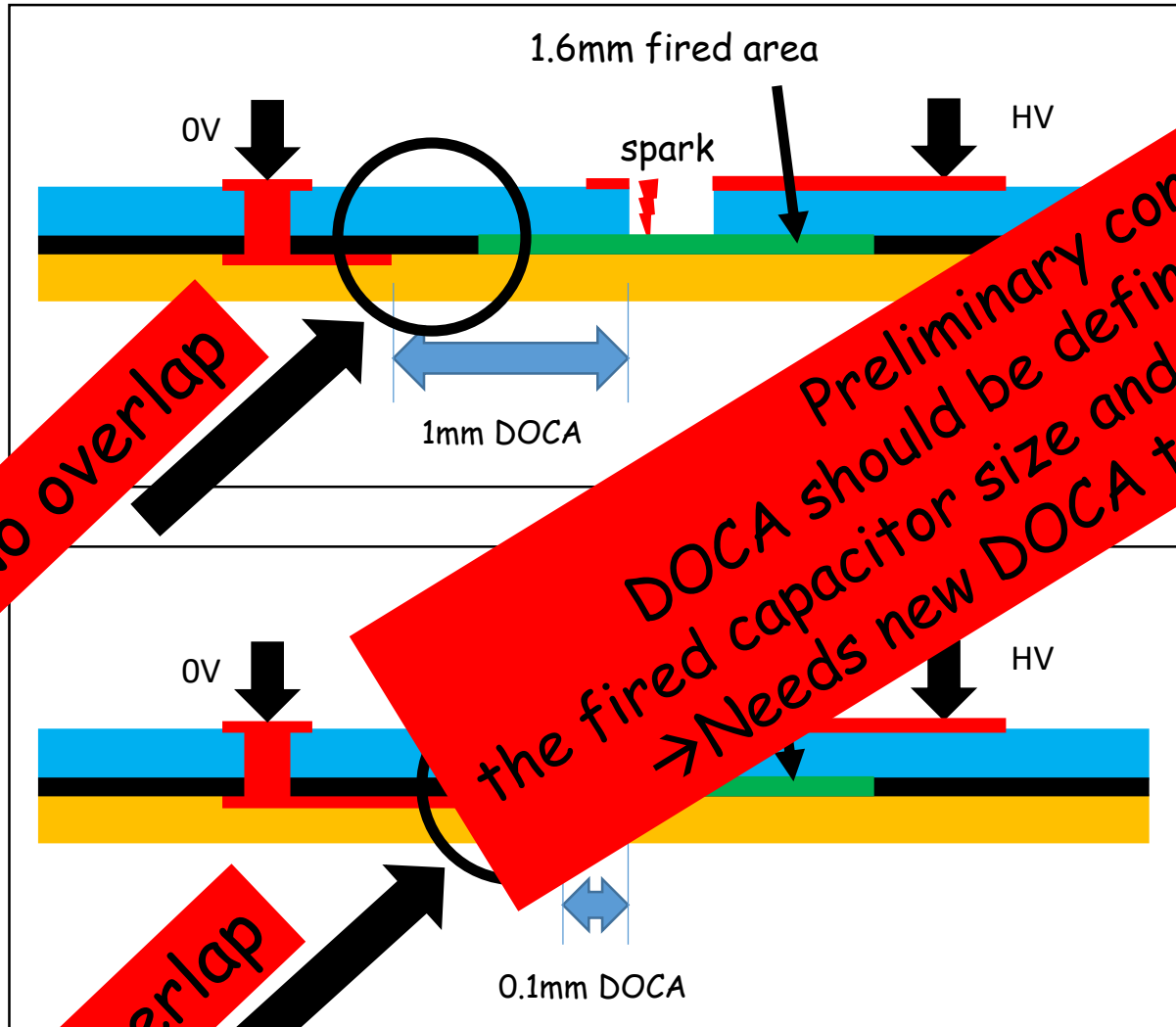
The spark energy comes from the fired area capacitor + HV connection + cabling + power supply effects

We loose control



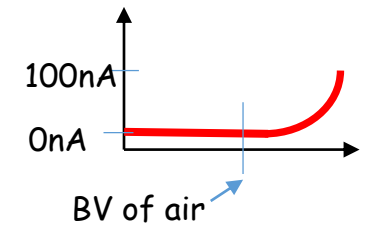


# Possible explanation of the DOCA Test



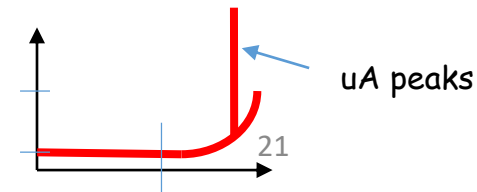
Energy comes only from  
area capacitor

We keep control



The spark energy comes from  
the fired area capacitor  
+ HV connection + cabling  
+ power supply effects

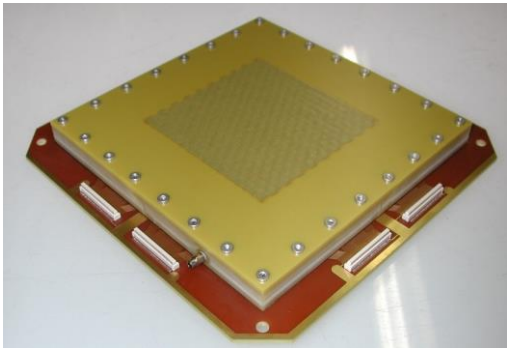
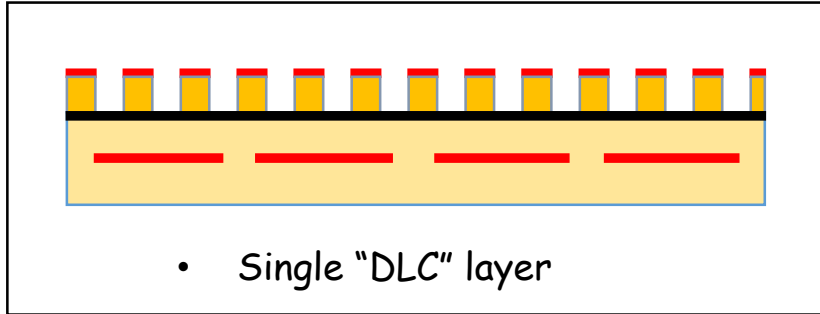
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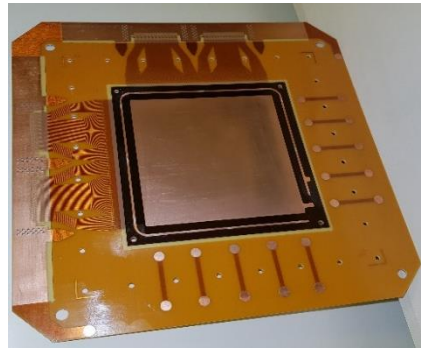
# Production

# Different $\mu$ Rwell structures

## $\mu$ Rwell

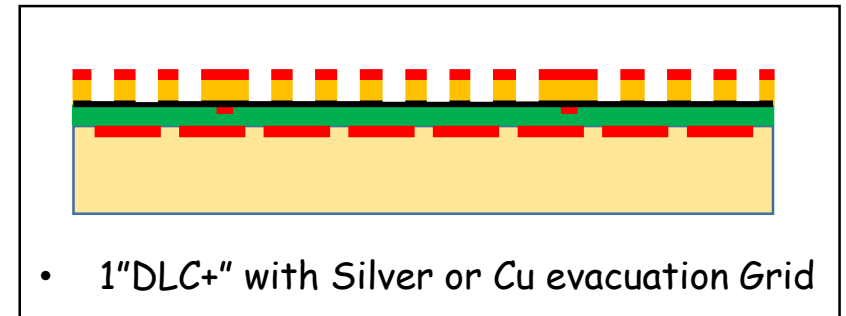


10cm x 10cm  
 $\mu$ Rwell detector  
"study kit"

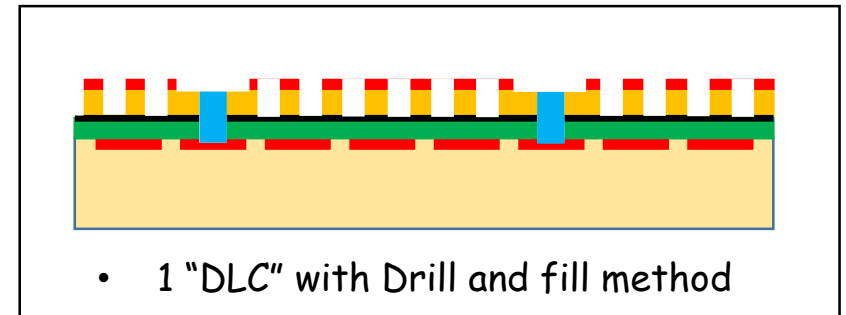


SG

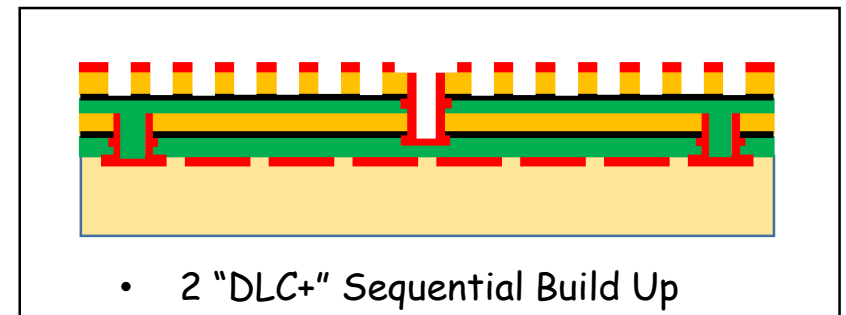
High rate detectors



DF



SBU



# SG type:

Silver/Cu Grid

"DLC+" 

R/O 

Make Grid 

R/O 

GLUE 

'Wellize' 

- Simple construction
- Adjustable evacuation point density VS rate

-Needs precise DOCA

-Needs "DLC+" Foils

-Large size detector registration

Cu strips 

DLC area

"DLC+" foil

DOCA : 0.25mm  
0.1mm grounding line  
0.6mm dead line

# DF Type

Drill and Fill

R/O



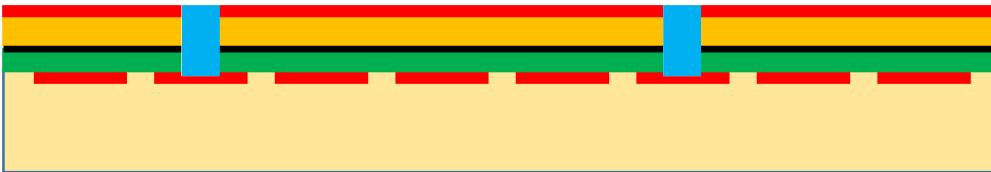
DLC  
gluing



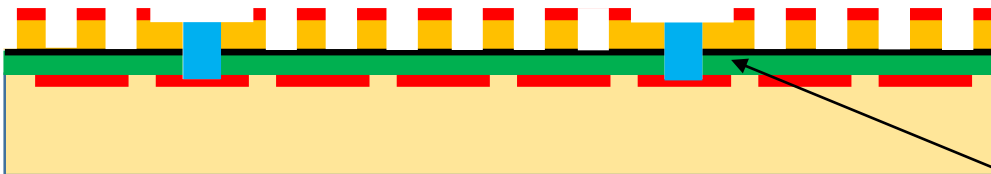
Drill



Fill



'Wellize'

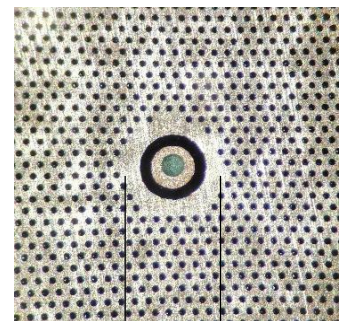
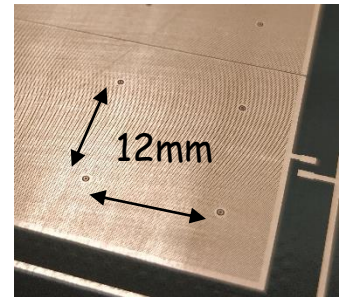
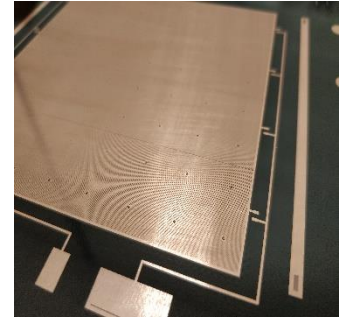


- Simple construction
- Adjustable evacuation point density VS rate
- Needs simple DLC foils
- No problem for large size production

-Needs precise DOCA

-DLC to silver contact need to be improved

DOCA : 0.25mm  
0.2mm hole  
0.7mm dead zone



0.7mm<sub>25</sub>

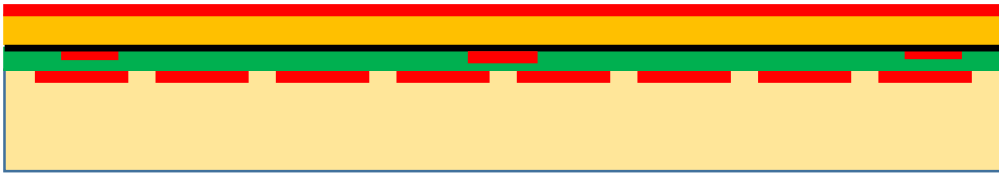
# SBU type

Sequential Build Up

R/O



DLC+  
Pattern Pads  
& Glue



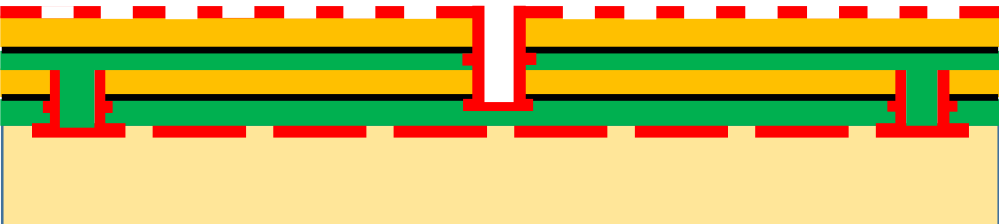
Drill  
Plate  
& Etch



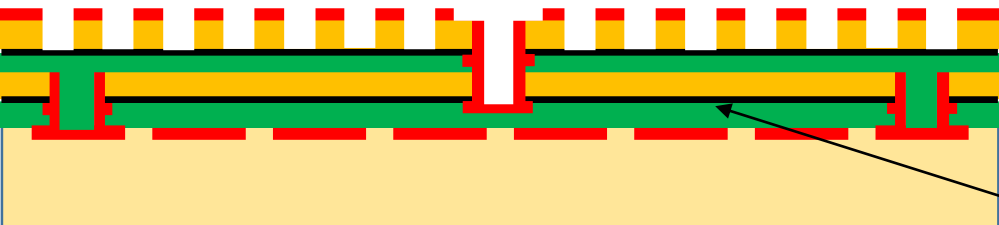
DLC+  
Pattern Pads  
& Glue



Drill  
Plate  
& Etch

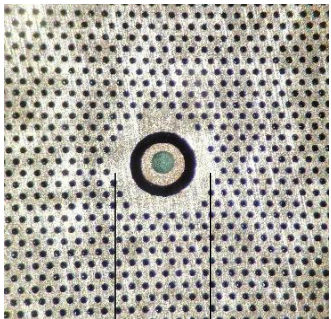
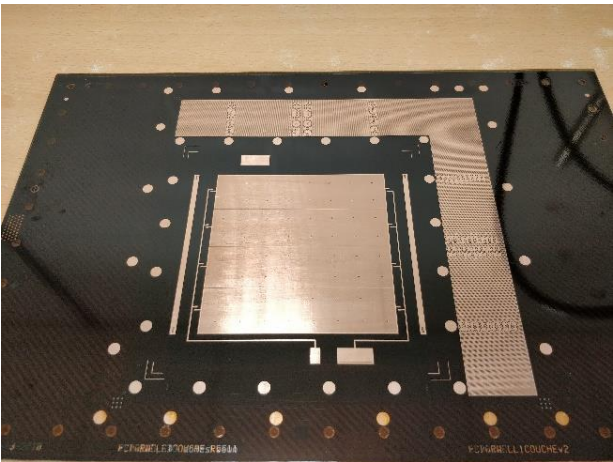


'Wellize'



- Extra Large DOCA
- Adjustable evacuation point density VS rate
- 100% compatible with STD PCB processes

-Needs DLC+ base material



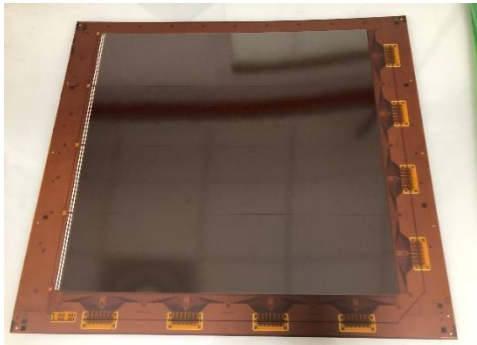
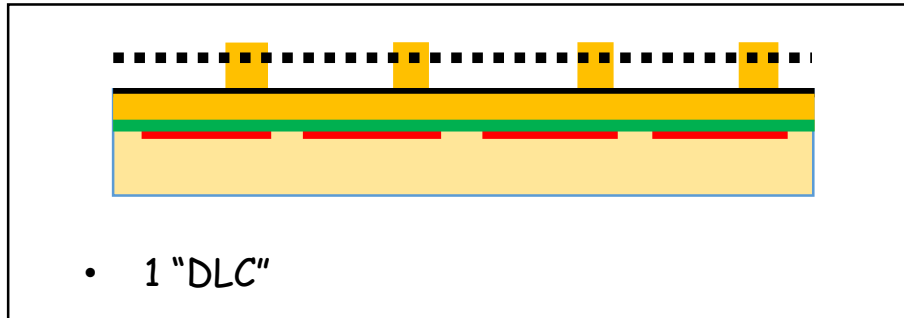
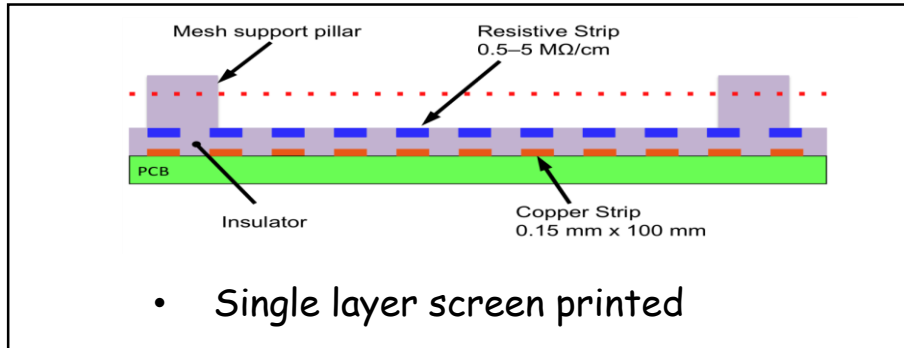
DOCA : 6mm

0.7mm<sup>26</sup>



# Different Resistive protection approach with Micro-Megas

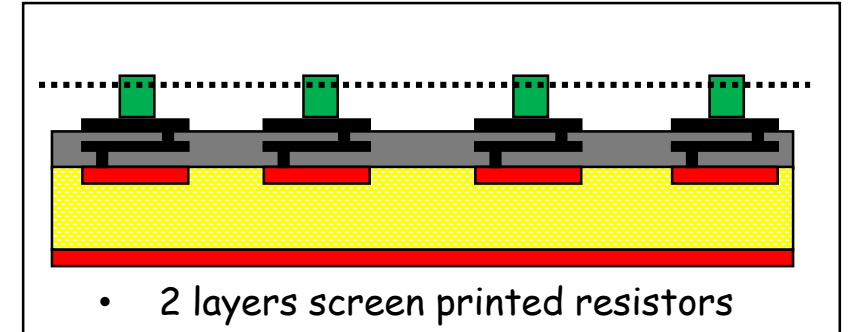
## Medium rate detectors



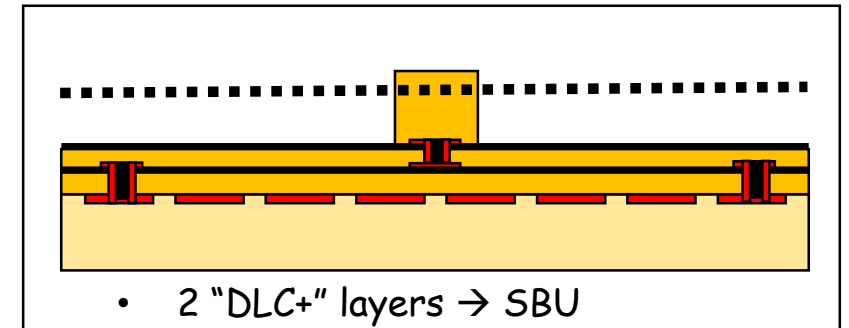
20 LSBB  
50cm x 50cm  
X/Y 1mm/1mm  
30M/Sqr sharing layer

Printed

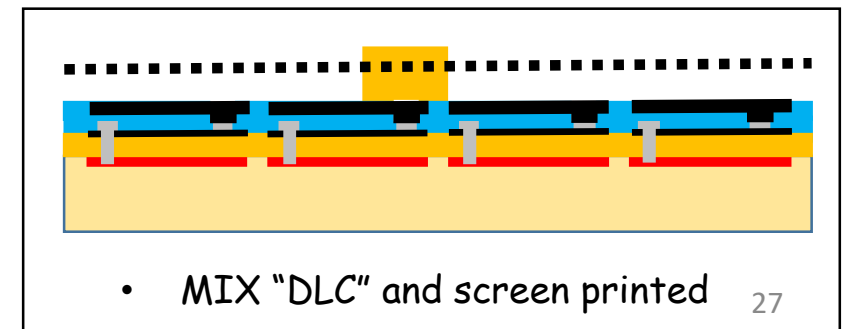
## High rate detectors



SBU



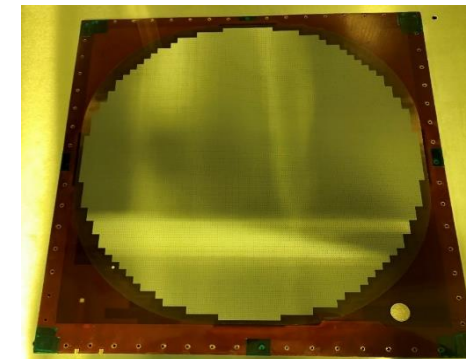
Mix



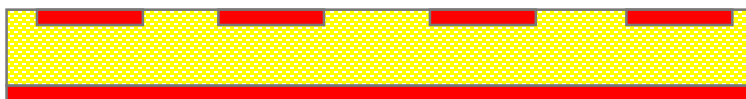
# 2 Printed layers

- Extra Large DOCA
- Accurate layers registration in large size
- No DLC needed
- High rate detectors

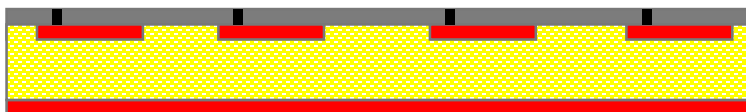
- Embedded Res should be less than 10KOhms/square
- Large pads only
- low energy resolution



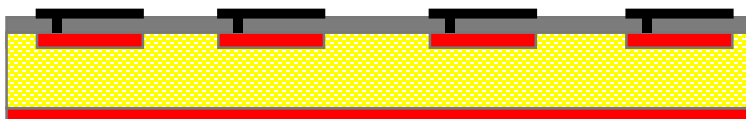
5 ILC DHCAL  
50cm diameter  
pads 1cm x 1cm  
5M/Pad



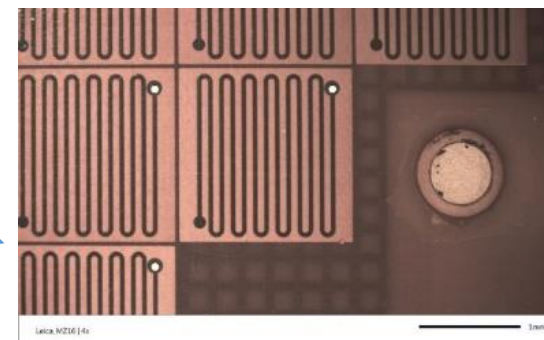
PCB



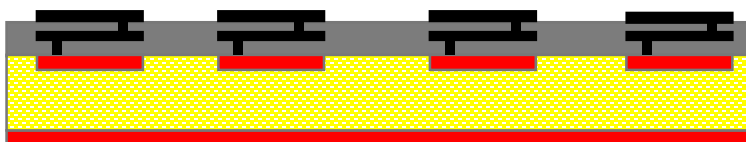
Coverlay gluing + drilling + via fill



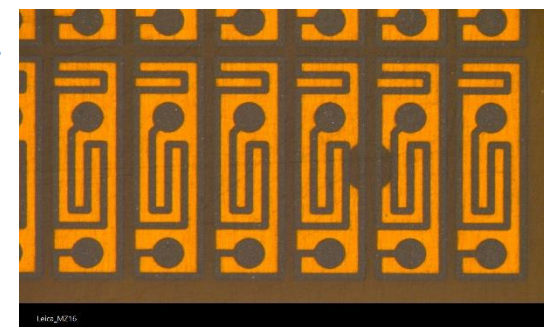
Resistive paste resistors  
(10KOhms/square max)



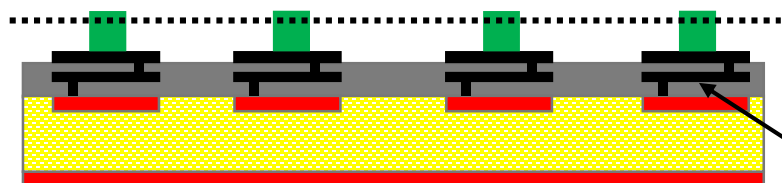
1cm x 1cm pad → Ok  
There is space to create a  
2 Mohms Resistor  
with 10K/sqr paste



Coverlay gluing + via fill  
+ top resistive printing (100K max)



1mm x 3mm pad → Bad result  
There is no space to create a  
2 Mohms Resistor  
with 10k paste



'BULKage'

DOCA: 10mm

## 2 "DLC+" structure with SBU process Sequential Build Up

PCB



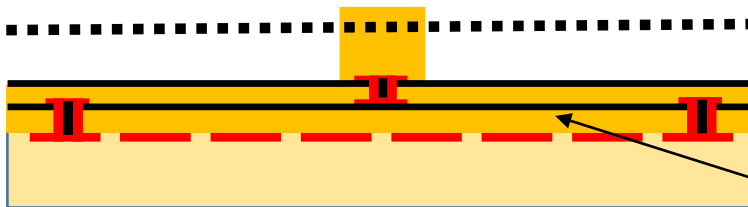
Glue "DLC+"  
drill  
Plate  
Pattern Cu



Glue "DLC+"  
drill  
Plate  
Pattern Cu

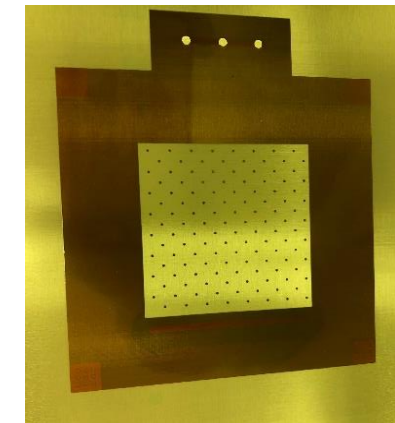
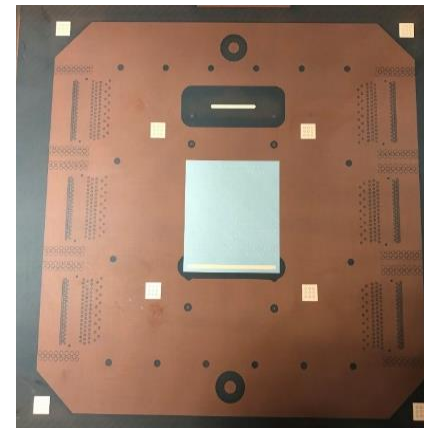


'BULKage'



- Extra Large DOCA
- Adjustable evacuation density VS rate
- no problem with layers registration
- good energy resolution
- 100% compatible with STD PCB processes

-Needs "DLC+"



DOCA: 3mm

# MIX method

PCB



DLC Gluing  
DLC pattern



Drilling



Coverlay  
Silver paste fill



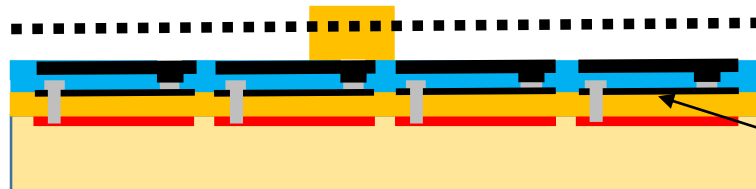
Coverlay



Res paste fill

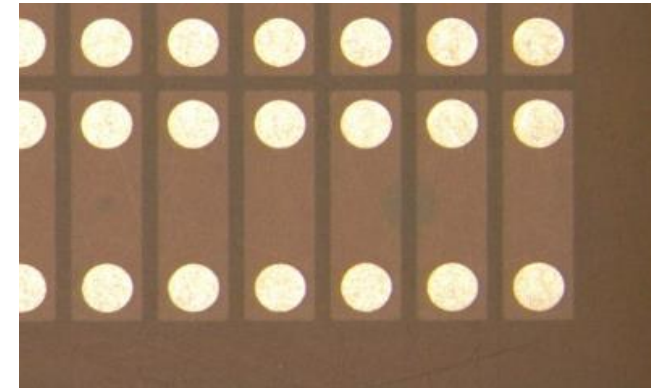
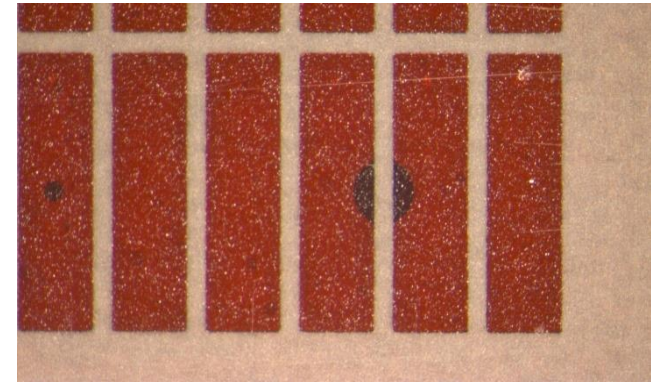


'BULKage'



- Large DOCA
- Maximized evacuation density points
- Needs simple DLC foils
- no problem with large size
- Ultra high rate detectors

-the filling technic is not STD in PCB world



DOCA: 2mm

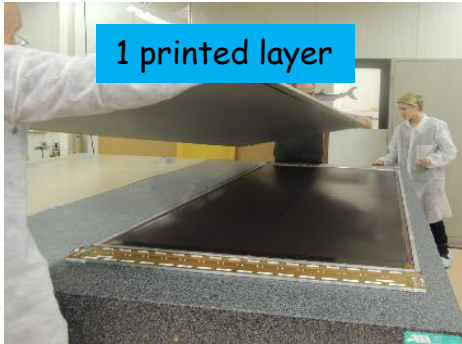
# conclusion

- Simple DLC material
  - Ready for large size and high rate detectors
  - For some application we need to get better resistive uniformity
- We need to improve the "DLC+" materials (Cu adhesion)
  - Main goal is to propose solutions 100% compatible with industry STD processes
  - There is still work to be done to produce large sizes "DLC+" foils
- DOCA & "Energy Release" study should be continued to optimize protection
  - Fine study of currents during quenched sparks

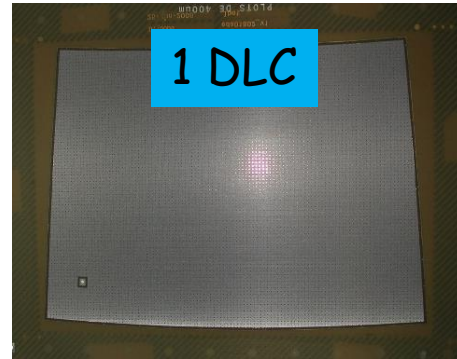
Thank you



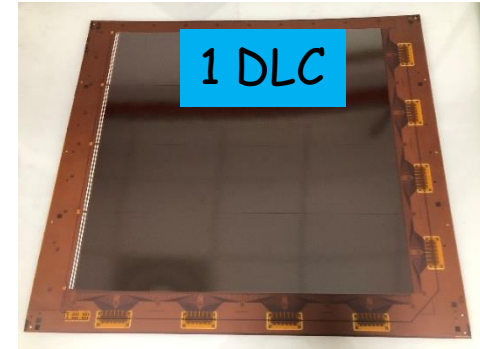
# examples:



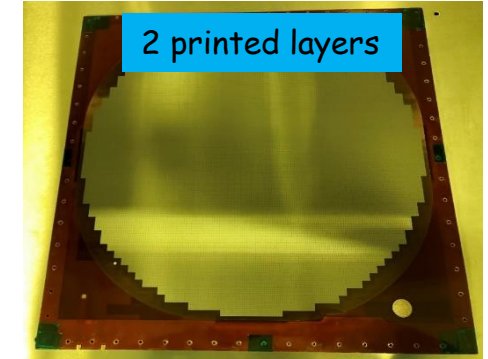
ATLAS NSW  
Strips 100k/Sqr  
2m x 1m



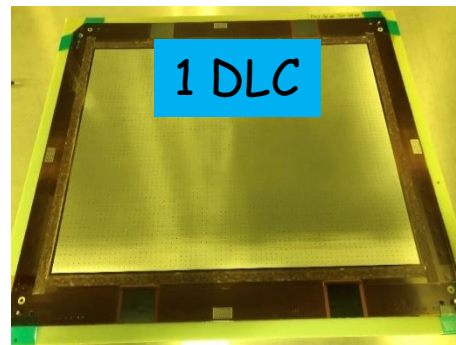
ILC TPC  
30cm x 15cm  
3mm x 8mm pads  
2M/Sqr sharing layer



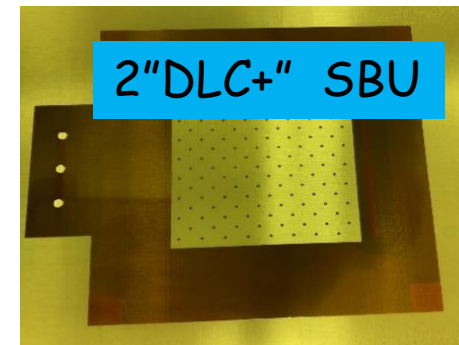
20 LSBB  
50cm x 50cm  
X/Y 1mm/1mm  
30M/Sqr sharing layer



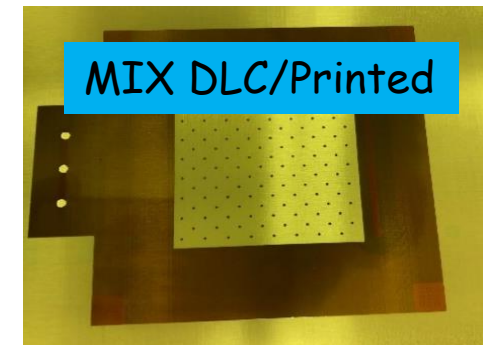
5 ILC DHCAL  
50cm diameter  
pads 1cm x 1cm  
5M/Pad



32 T2K upgrade  
40cm x 40cm  
1cm x 1cm pads  
500K/Sqr sharing layer



2 Demonstrator  
5cm x 5cm  
1mm x 3mm pads  
2R layers 30M/5M  
2R layers 60M/60M



2 Demonstrators  
5cm x 5cm  
pads 1mm x 3mm  
5 M/pad  
20M/pad

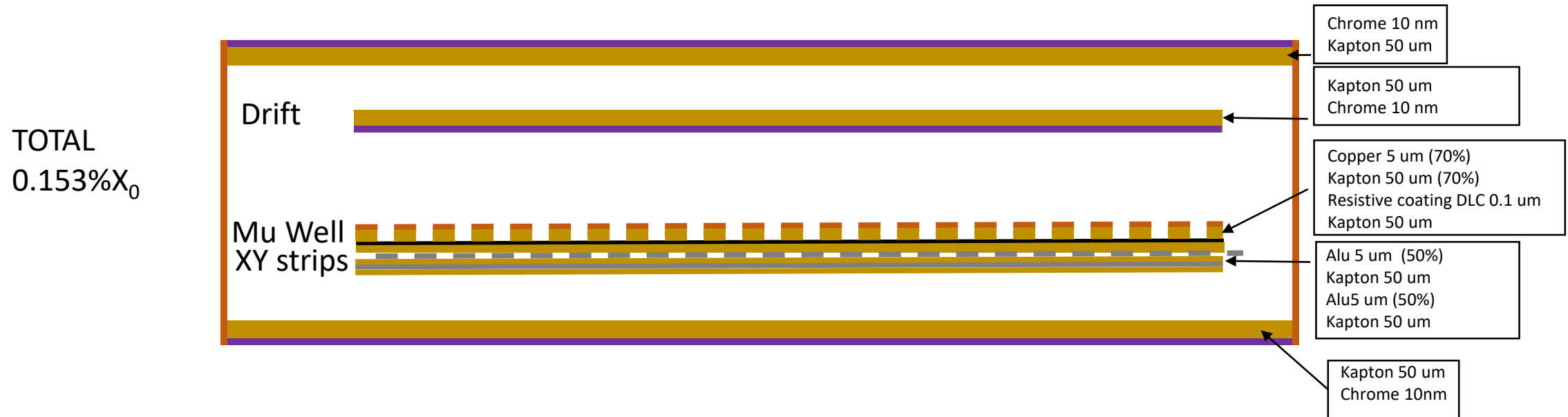
TOTEM  
GEM

Item	Details	$^{\circ}/_{oo}$ of $X_o$
3 GEMs	6 x 5 $\mu\text{m}$ copper [0.7]	1.68
	3 x 50 $\mu\text{m}$ kapton [0.7]	0.42
	TOTAL:	2.10
1 Drift	5 $\mu\text{m}$ copper	0.35
	50 $\mu\text{m}$ kapton	0.17
	TOTAL:	0.52
3 Grid spacers	3 x 2 mm fiberglass [0.008]	0.25
1 Readout board	80 $\mu\text{m}$ strips: 5 $\mu\text{m}$ copper [0.2]	0.07
	1536 pads: 5 $\mu\text{m}$ copper [0.85]	0.26
	50 $\mu\text{m}$ kapton [0.2]	0.03
	120 $\mu\text{m}$ fiberglass	0.62
	60 $\mu\text{m}$ epoxy	0.30
	TOTAL:	1.28
1 Shielding	10 $\mu\text{m}$ aluminium	0.11
2 Honeycombs	2 x 3 mm Nomex	0.46
4 Fiberglass foils	4 x 120 $\mu\text{m}$ fiberglass	2.47
	TOTAL:	7.19

**TOTAL**  
**0.719 % $X_0$**

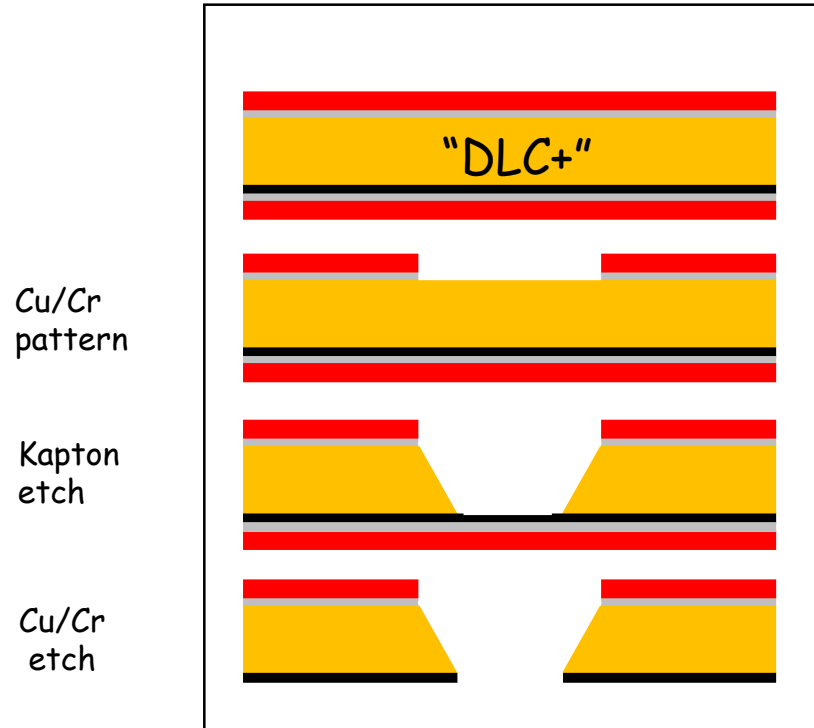
*Table 1.1: Material in one GEM detector*

# Micro Well with XY aluminum strip , Chrome drift

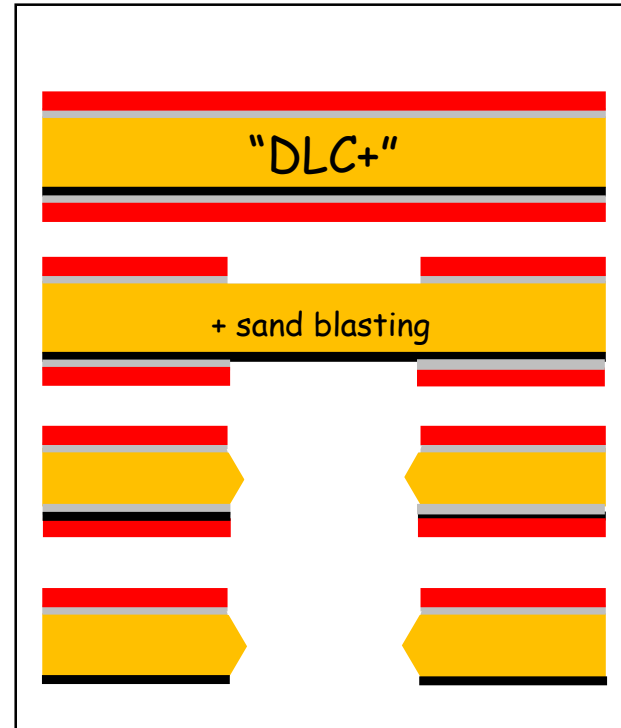


Conservative approach, copper is used in the place of avalanche discharges.  
If we use only aluminum it makes  $0.16\%X_0$

# DLC Resistive GEM

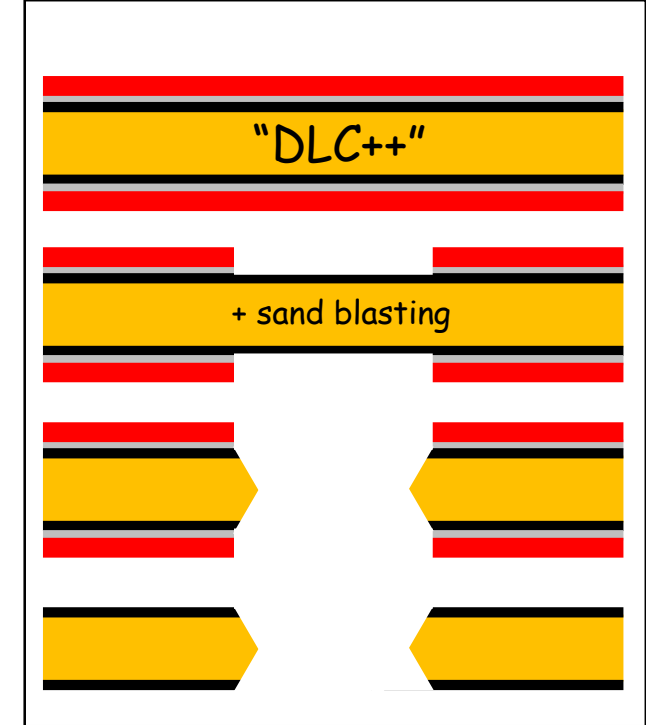


FTM process

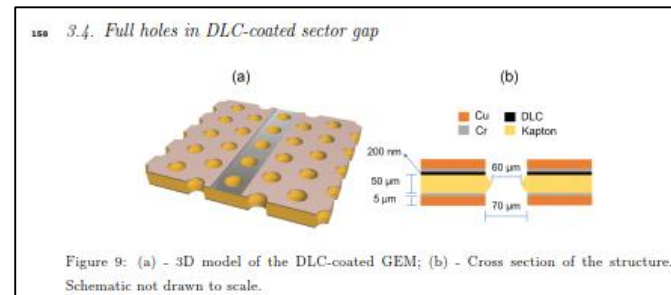


Minimizing distortions with sectorized GEM electrodes

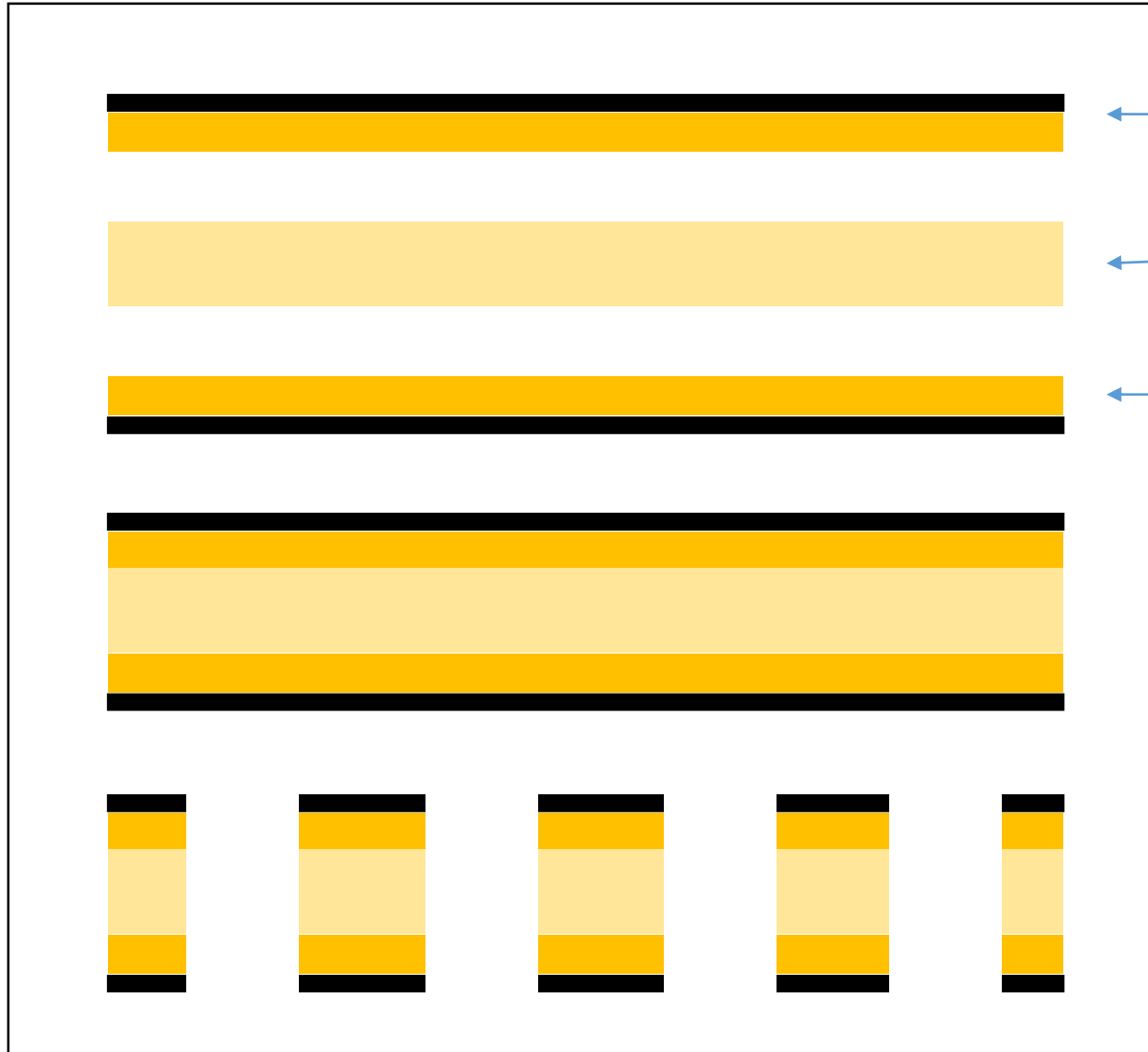
A.P. Marques<sup>a,b</sup>, F.M. Brumbauer<sup>a,\*</sup>, H. Müller<sup>a</sup>, R. de Oliveira<sup>a</sup>, E. Oliveri<sup>a</sup>,  
D. Pfeiffer<sup>a,c</sup>, L. Ropelewski<sup>a</sup>, J. Samarati<sup>a,c</sup>, F. Sauli<sup>a</sup>, L. Scharenberg<sup>a,d</sup>,  
L. Shang<sup>e</sup>, M. van Stenis<sup>a</sup>, S. Williams<sup>a</sup>, Y. Zhou<sup>f</sup>



In progress  
Waiting for good base material



# Resistive THGEM



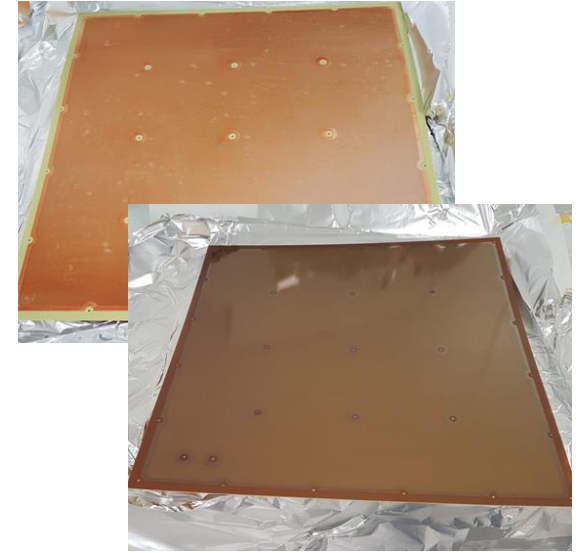
← Kapton with DLC

← PCB

← Kapton with DLC

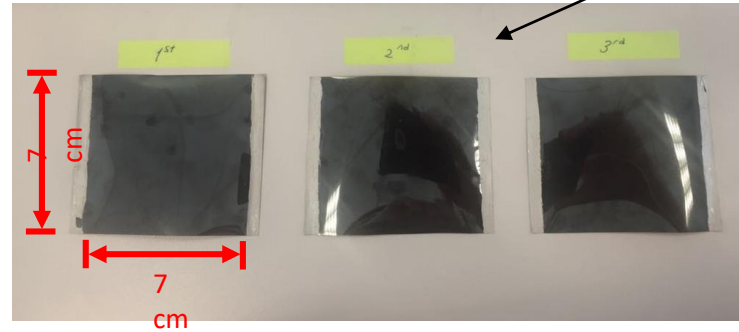
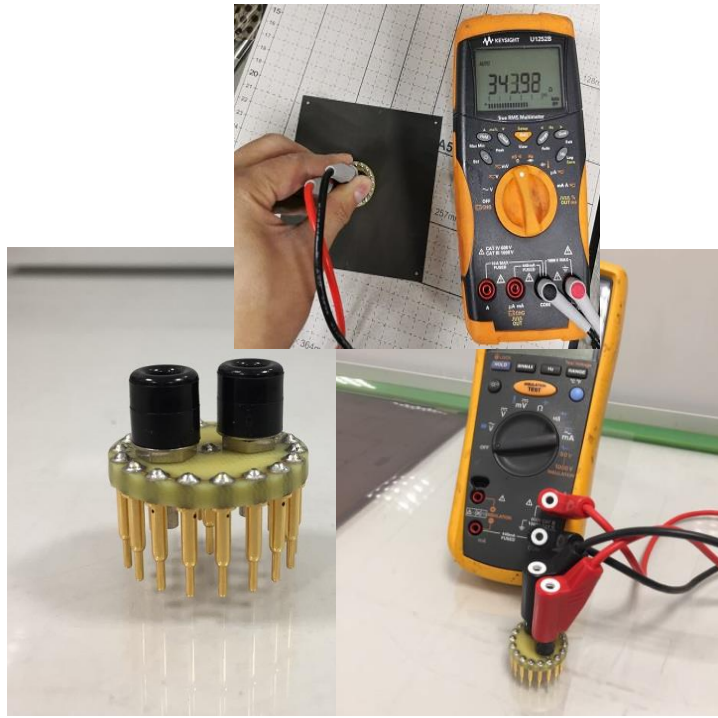
Glue the 3 parts with prepreg

Drilling like a THGEM



# Resistive measurements

## Probe calibration



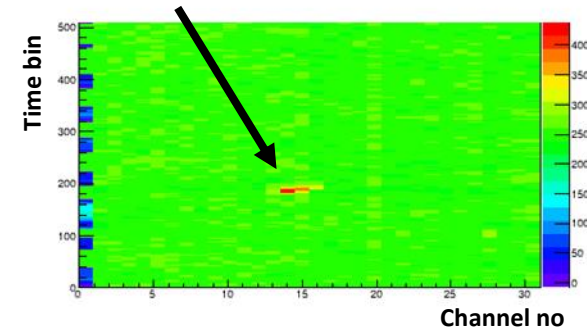
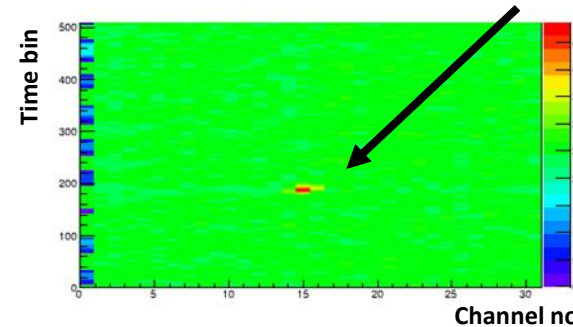
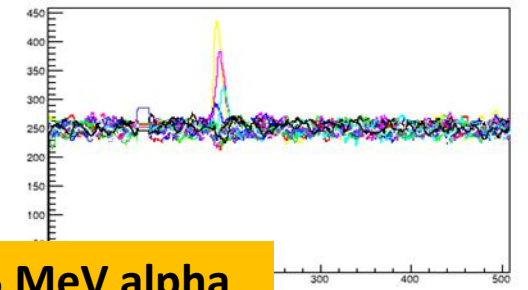
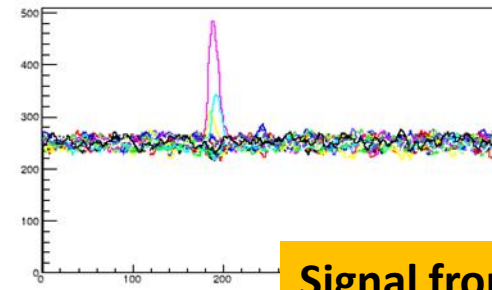
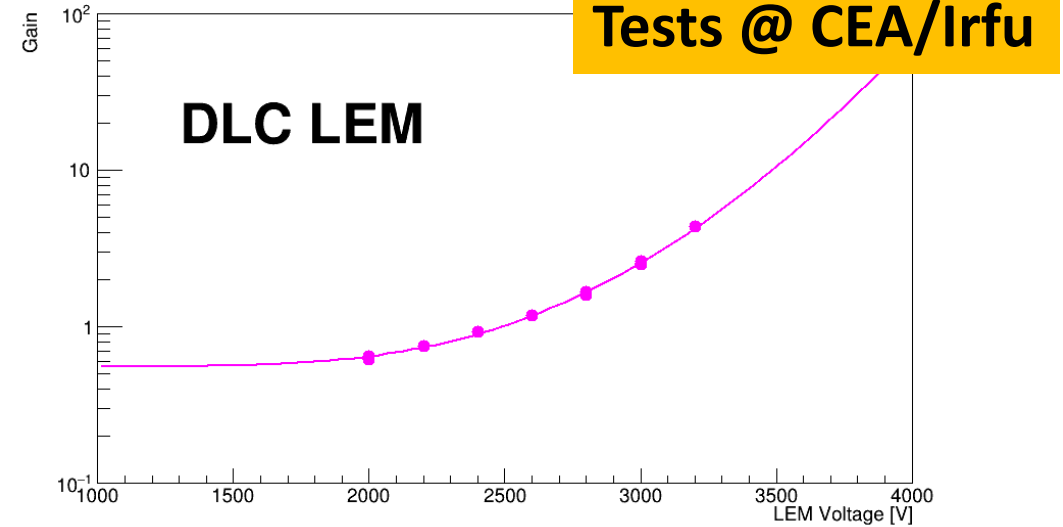
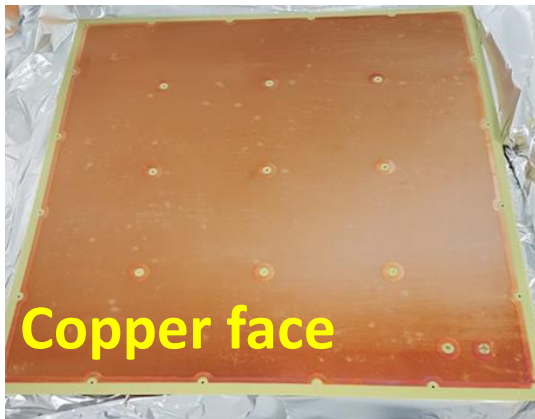
- 7cm x 7cm square of DLC
  - lateral silver connection to create 1 Square
- Connect probe to Ohm-meter
- Compare probe measurement to silver connections measurement
- Error in the range of 5%
- We can directly read the value from the Ohm-meter

DLC Film	Surface Resistivity (k $\Omega$ / $\square$ )	Surface Resistance From The Probe (k $\Omega$ )	Coefficient Factor	Error (%)
1	359	345	1.041	4
2	386	364	1.060	6
3	403	380	1.061	5



# Resistive LEM

- Quenching of discharges with resistive 50×50 cm<sup>2</sup> LEM :
- Made at CERN EP-DT-EF :
  - copper side facing readout anode
  - DLC on 50 μm APICAL polyimide film (250 MΩ/□)
  - same geometry as CFR-35 (ProtoDUNE-DP)
  - no rims, no gold plating on copper face.
- Tests in progress at CEA/Irfu.
- R&D will continue in collaboration with CERN.



# Goal of resistive protections

- Make Sparks invisible
- Simplify detectors
  - Reduce the cost
  - Be large size compatible
  - Aim to use only industrial processes
- Keep best "existing" MPGDs features
  - Rate
  - Space resolution
  - Time resolution
  - Energy resolution
  - Mass